



Energetic Condensation Growth of Nb films for SRF Accelerators *

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presented at

SRF-2011, Tuesday July 26, 2011

This research is supported at AASC by DOE via Grant DE-FG02-08ER85162 and Grant DE-SC0004994

The JLab effort was provided by Jefferson Science Associates, LLC under U.S. DOE Contract No. DE-AC05-06OR23177, including supplemental funding provided by the American Recovery and Reinvestment Act

- ◆ Motivation for thin films in SRF cavities
- ◆ History of thin film development
- ◆ Energetic Condensation
- ◆ Morphology of thin films produced by energetic condensation
- ◆ Thin films on Cu
- ◆ Future Plans

Motivation

- ◆ More than 10000 particle accelerators worldwide; most use *normal* cavities
 - ◆ Facility for Rare Isotope Beams (FRIB), II C
❖ NSAC report states that as a result of technological advances, a large facility can be built at \approx half the cost originally planned by employing a superconducting linac
 - ◆ SRF at 2K is still operating at cryogenic cooling moves toward shelf cryo-coolers as the cryogenic cooling moves toward shelf cryo-coolers as the
 - ◆ Replacing bulk Nb with Cu coated Cu cavities also reduce costs
 - ◆ The ultimate goal would be from just Al SRF cavities coated with higher temperature superconductors (Nb₃N, Mo₃Re, Nb₃Sn, MgB₂, oxypnictides)
- SRF uses less power than normal*
- SRF with cheaper cavity materials (Cu) would be better*
- SRF with cheaper cavity materials and high-T_c thinfilms would be better still*

AASC's thin film superconductor development is aimed at these goals

Two examples of early SRF thin film development

LEP at CERN tested Cu cavities Magnetron sputter coated with ~1.5 μ m Nb thin films (1984-)

- ◆ C. Benvenuti, N. Circelli, M. Hauer, Appl. Phys. Lett. 45, 1984. 583; C. Benvenuti, Part. Accel. 40 1992. 43; C. Benvenuti, S. Calatroni, G. Orlandi in: 20th International conference on Low Temperature Physics, Eugene 1993, to be published in Physica B; C. Benvenuti, S. Calatroni, I.E. Campisi, P. Darriulat , M.A. Peck, R. Russo, A.-M. Valente, Physica C316, 1999, 153–188, (Elsevier): *Study of the surface resistance of superconducting niobium films at 1.5 GHz*
 - *RRR=11.5 on oxide coated Cu, 29 on oxide-free Cu coated at 150° C*
- ◆ G. Amolds, Doktorarbeit, University of Wuppertal, WUB 79-14 (1979)
 - *Wuppertal studied 8, 3 and 1GHz Nb cells vapor deposition coated with Nb₃Sn*

Thin Film Cavities & Q-Drop

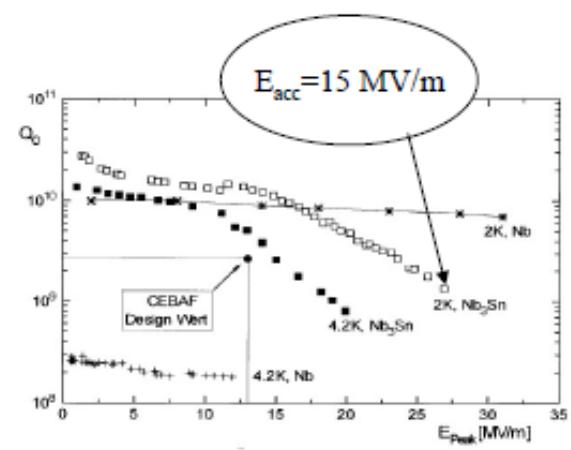
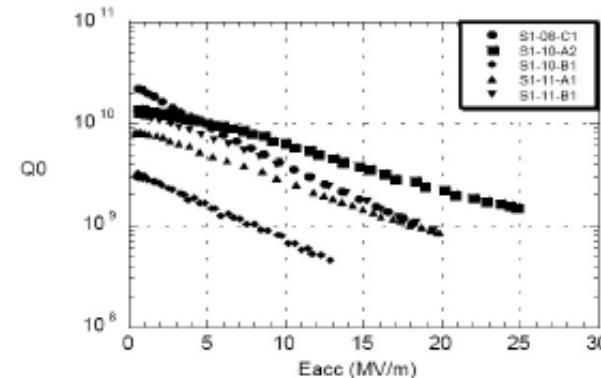
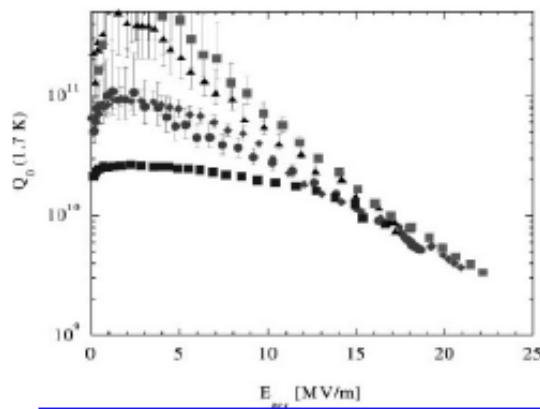
dapnia

cea

saclay

Advantages to use Thin Film Technology for SRF Cavities :
Reduced Cost - New Superconducting Material (higher T_c & H_{sh})

severe Q-drop limits High Gradient Performances $E_{acc} < 25 \text{ MV/m}$

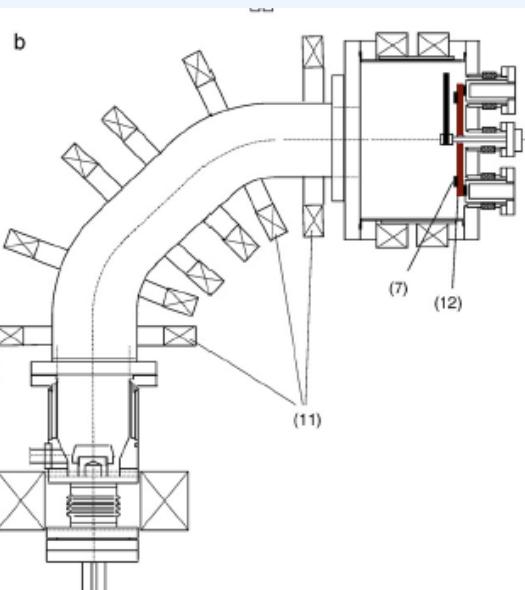


CERN - Nb / Cu - 1.5 GHz
Magnetron Sputtering in Kr
V. Arbet-Engels et al. - NIMA (2001)

Saclay - Nb / Cu - 1.5 GHz
Magnetron Sputtering in Ar
P. Bosland et al. - ASC (1998)

Wuppertal - Nb₃Sn / Nb - 1.5 GHz
Vapor Deposition Technique
G. Müller et al. - EPAC (1996)

(no field emission, no quench only RF power limitation)

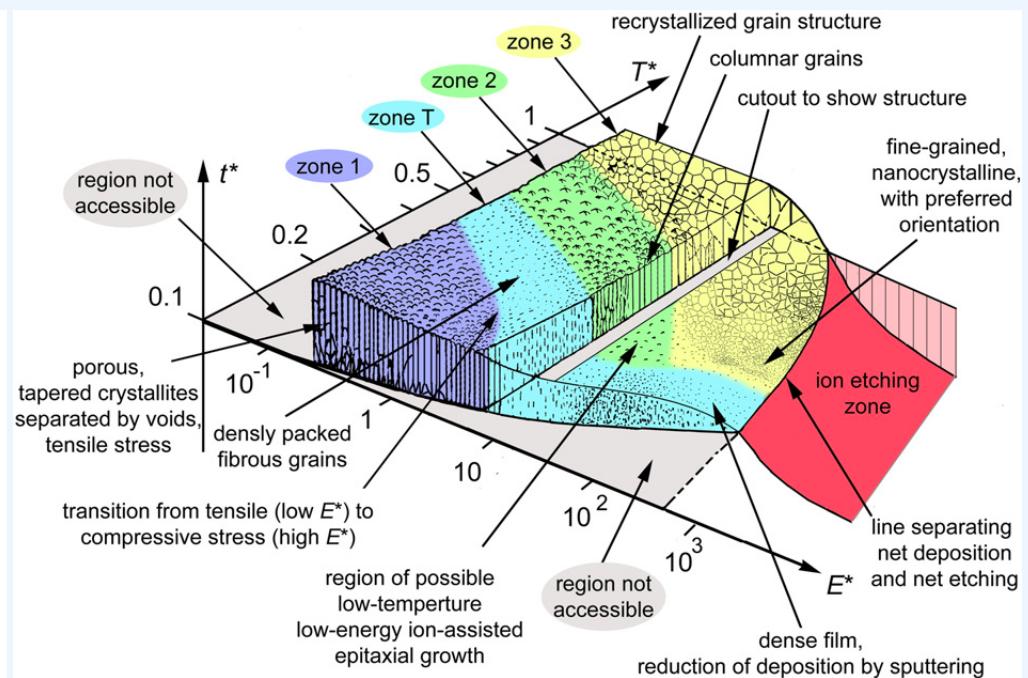
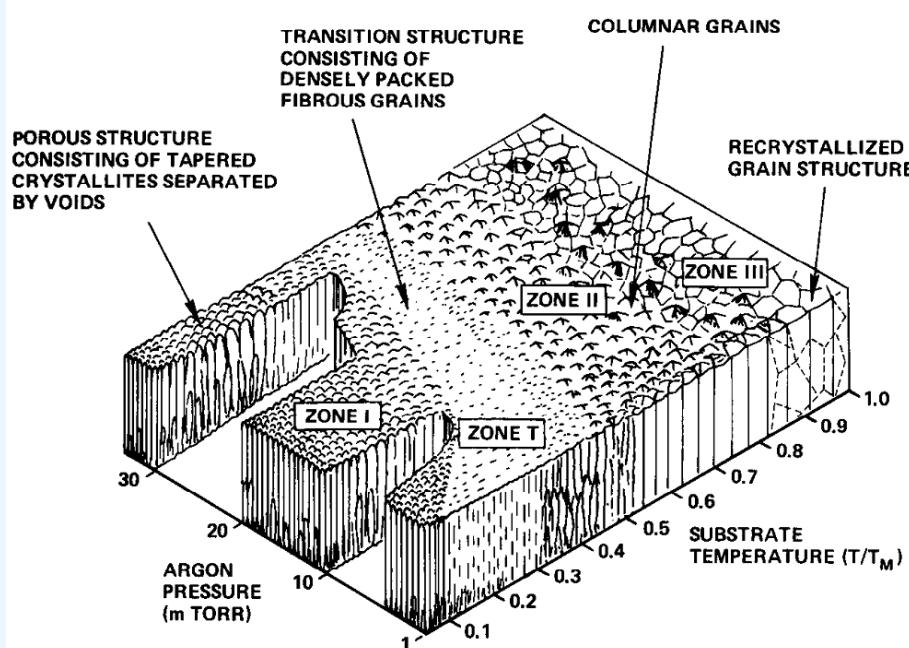


- ◆ R. Russo, A. Cianchi, Y.H. Akhmadeev, L. Catani, J. Langner, J. Lorkiewicz, R. Polini, B. Ruggiero, M.J. Sadowski, S. Tazzari, N.N. Koval, *Surface & Coatings Technology* 201 (2006) 3987–3992
 - Base pressure of $1\text{--}2 \times 10^{-10}$ mbar in the system is reached after one night bake at 150 °C, but pressure increased to 10^{-7} mbar during run
 - Laser trigger to minimize impurities in Nb film
 - Magnetic sector filter to reduce macro-particles in film
 - Lattice parameter (from XRD spectra) showed **much lower stress** than observed in niobium deposited by magnetron sputtering
 - Surface roughness was ~few nm on sapphire and on Cu, was comparable to that of the Cu substrate itself
 - RRR of 20-50 was measured on $\sim 1\mu\text{m}$ Nb films deposited on Quartz at room temperature (higher than typical sputtering values)

RRR up to 80 was reported with substrate heated to 200°C
 - Dominant impurity was H atoms outgassed from Nb cathode (needed careful bakeout of cathode to minimize this problem)
- ◆ J. Langner, R. Mirowski, M.J. Sadowski, P. Strzyzewski, J. Witkowski, S. Tazzari, L. Catani, A. Cianchi, J. Lorkiewicz, R. Russo, *Vacuum* 80 (2006) 1288–1293

- ◆ Motivation for thin films in SRF cavities
- ◆ History of thin film development for SRF cavities
- ◆ Energetic Condensation (a very brief primer)
- ◆ Morphology of thin films produced by energetic condensation
- ◆ Thin films on Cu
- ◆ Future Plans

Energetic Condensation



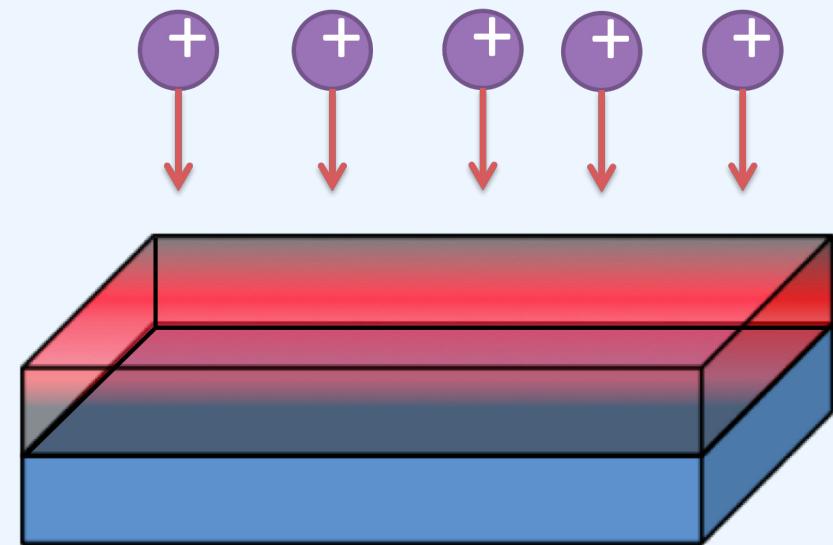
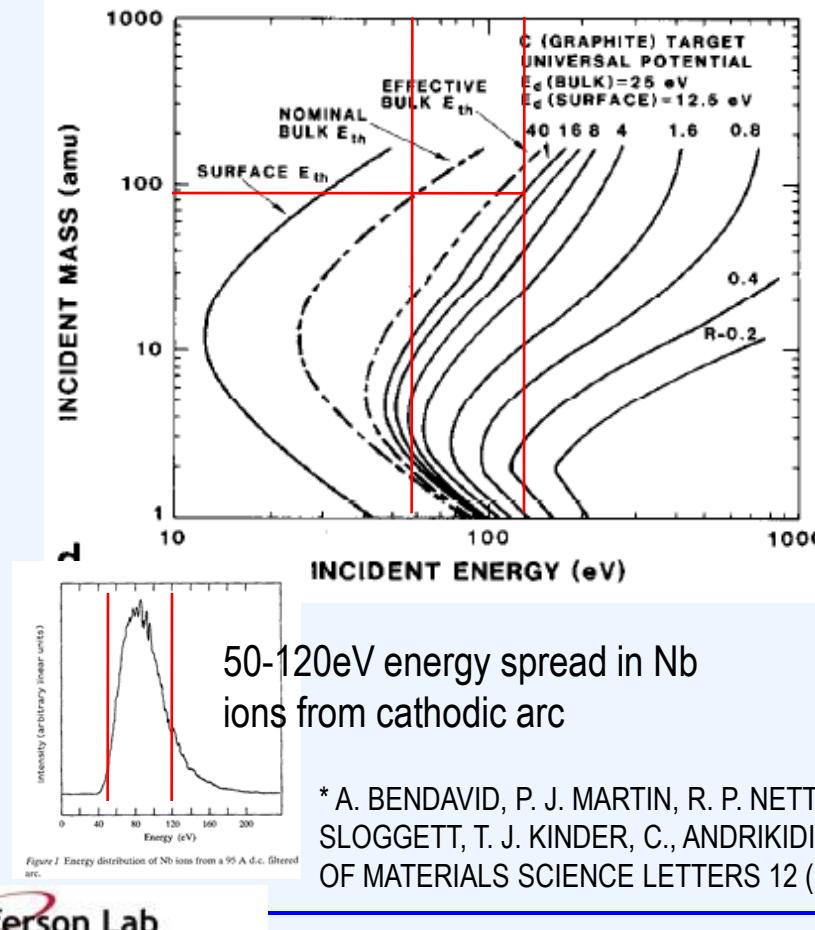
J.A. Thornton, "Influence of substrate temperature and deposition rate on the structure of thick sputtered Cu coatings", J. Vac. Sci. Technol. Vol. 12, 4 Jul/Aug 1975

Andre Anders, A structure zone diagram including plasma-based deposition and ion etching, Thin Solid Films 518 (2010) 4087–4090

- ◆ In Energetic Condensation, the ions deposit energy in a sub-surface layer (≈ 3 atomic layers deep for $\sim 100\text{eV}$ Nb ions), shaking up the lattice, causing adatom mobility and promoting epitaxial crystal growth
- ◆ Energetic Condensation when combined with substrate heating promotes lower-defect crystal growth

Subplantation Models

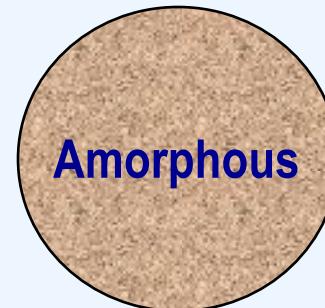
- ◆ Y. Lifshitz, S. R. Kasi, J. Rabalais, W. Eckstein, Phy. Rev. B Vol. 41, #15, 15 May 1990-II:
Subplantation model for film growth from hyperthermal species
- ◆ D.K. Brice, J.Y. Tsao and S.T. Picraux: PARTITIONING OF ION-INDUCED SURFACE AND BULK DISPLACEMENTS
- ◆ W. D. Wilson, Radiat. Eff. 78, 11 (1983)



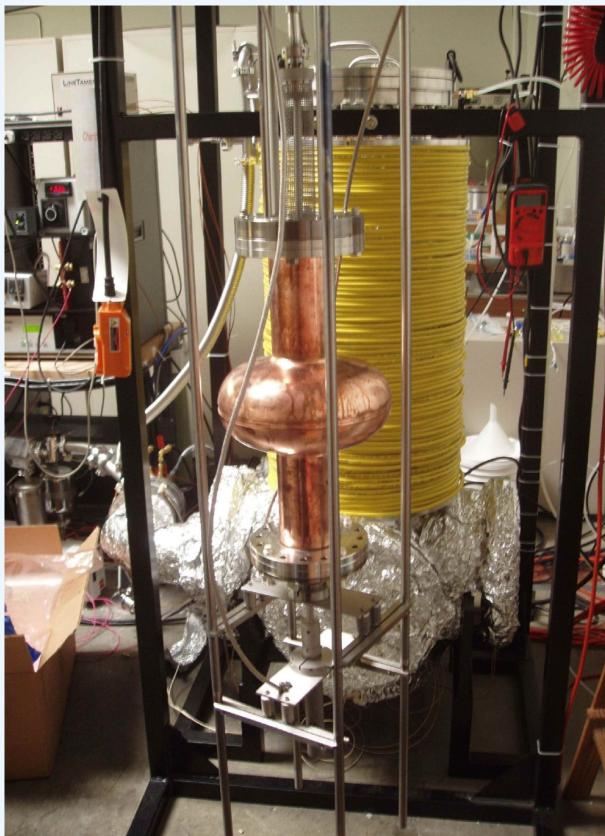
Thermal-Vacuum Stability of the Surface Oxide Complex on Cu

M. Bagge-Hansen, R.A. Outlaw, K. Seo, C. Reese, J. Spradlin, Anne Marie Valente-Feliciano and D.M. Manos, Journal of Vacuum Science and Technology (2011), in press

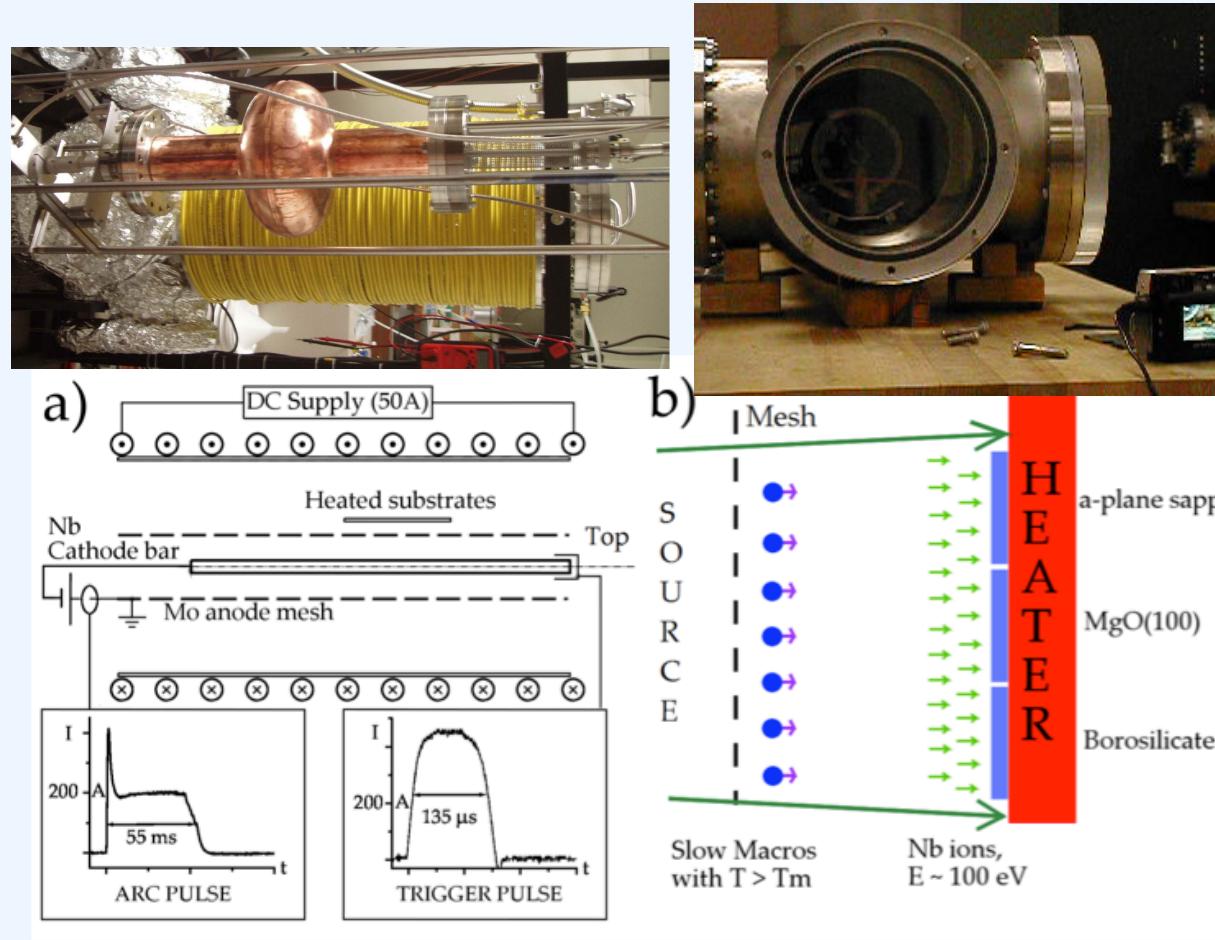
- ◆ Cu and/or Al cavity substrates might be of two different forms



- ◆ How do we grow low-defect Nb films on such substrates?
- ◆ Study adhesion, thickness, smoothness, RRR, stability
- ◆ Understand these issues at the coupon level
- ◆ Proceed to RF cavity level and measure Q at high fields
- ◆ Install multi-cell Nb coated Cu modules in SRF accelerator and validate the thin film solution
 - ◊ Spur acceptance of thin film Nb by accelerator community
- ◆ Continue R&D towards higher T_c films and Al cavities



**Coaxial Energetic Deposition
(CED™)**



- ◆ CED coater uses “welding torch” technology
- ◆ Arc source is scalable to high throughputs for large scale cavity coatings
 - Present version deposits \approx 1 monolayer/pulse in \approx 1ms
- ◆ Russo’s and Langner’s emphasis on UHV and clean walls is important

CAD: Pulsed Biased deposition; Dual Targets



Cathodic Arc Deposition (CAD)



Pulsed Bias capability

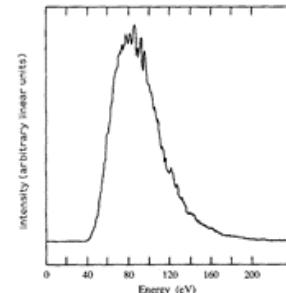
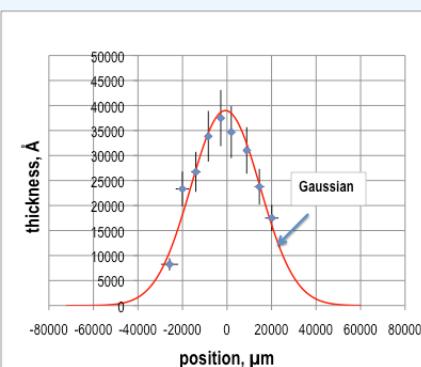
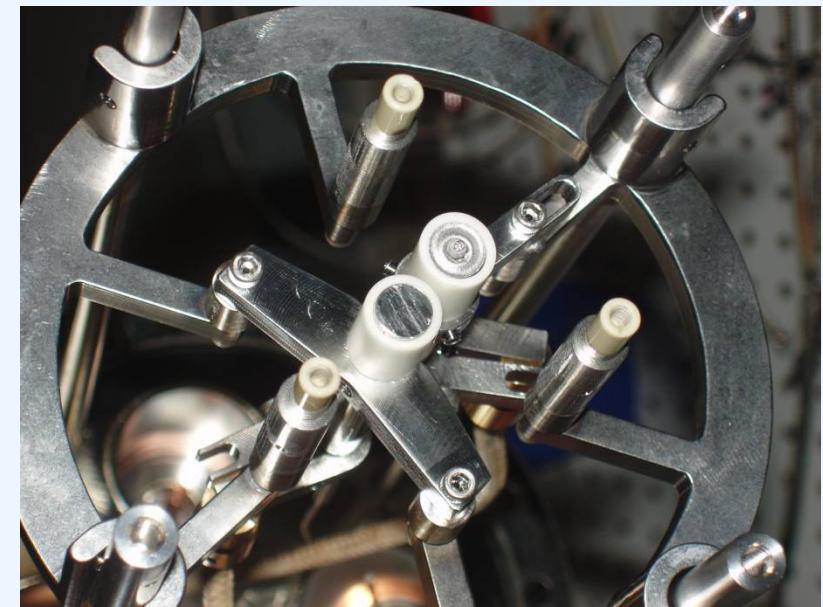


Figure J Energy distribution of Nb ions from a 95 A d.c. filtered arc.

* A. BENDAVID, P. J. MARTIN, R. P. NETTERFIELD, G. J. SLOGGETT, T. J. KINDER, C., ANDRIKIDIS, JOURNAL OF MATERIALS SCIENCE LETTERS 12 (1993) 322-323



vol under gaussian=	0.012	cc
mass under gaussian=	0.100	g
mass/shot=	14.3	μg
charge/shot=	0.5	C
anode transm.=	0.7	
erosion rate=	41	μg/C
peak thickness/pulse=	5.6	Å
instant. rate=	5600	Å/s



Dual Target source for Nb_3Sn , Mo_3Re , MgB_2 etc.

Please visit Poster THPO077 on Thursday: "Mo-Re Films for SRF Applications", Dr. Enrique Valderrama

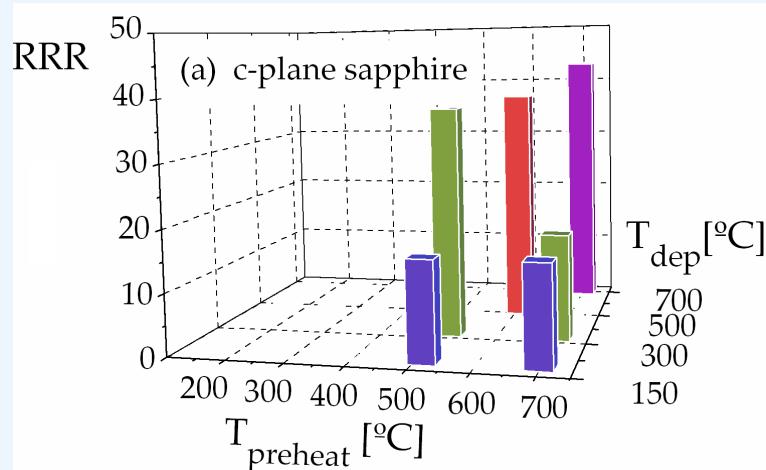
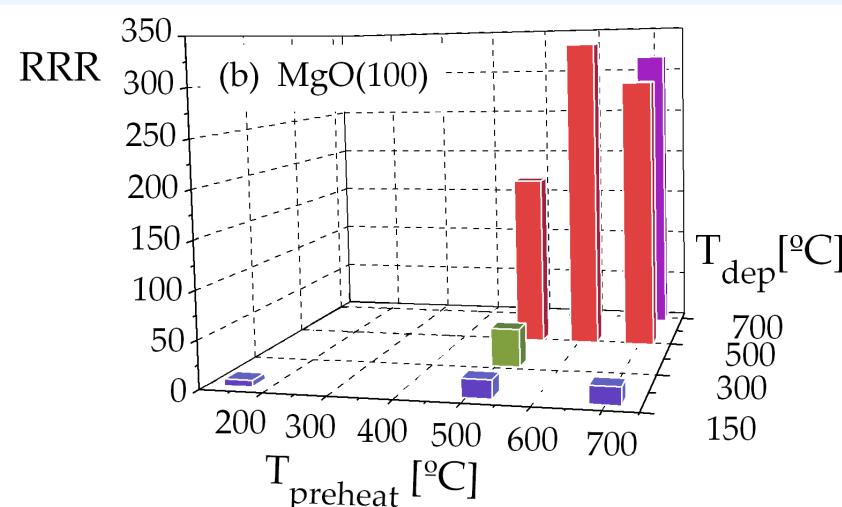
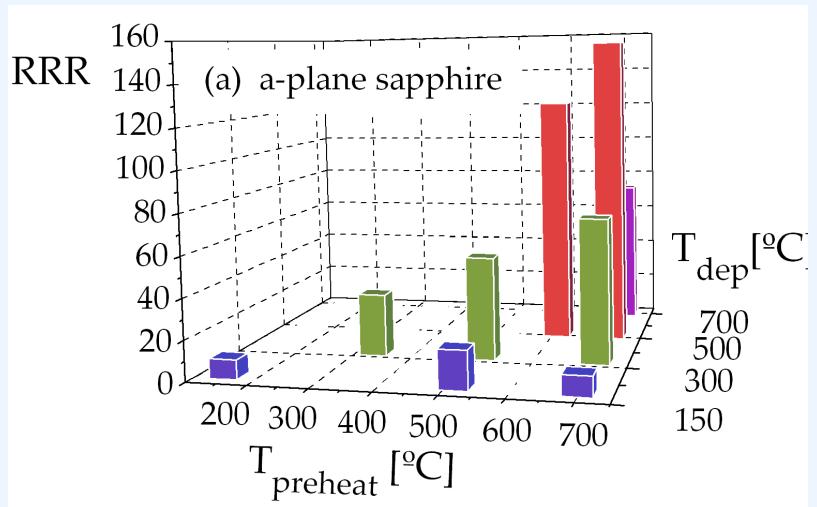
- ◆ AASC's UHV Arc coater (CED/CAD) and JLab's ECR source are both Energetic Condensation Coaters
 - ◊ The CED/CAD plasma generates Nb²⁺ and Nb³⁺ ions with 40-120eV energy spread
 - ◊ The ECR plasma also produces ~100eV ions by biasing the substrate, with Nb¹⁺ ions
- ◆ AASC and JLab collaborate on thin film development for SRF. Over the past year, we have achieved record RRR values in Nb films
 - ◊ RRR=585 in Nb on MgO using CED
 - ◊ RRR=488 in Nb on a-sapphire using ECR
 - ◊ RRR=289 in Nb on LG Cu using ECR
- ◆ We are learning more about the epitaxial growth modes on different substrates, building a knowledge base from which to proceed to Cu cavity coatings in the near future

Please see A-M Valente Feliciano's talk later in this session!

- ◆ Motivation for thin films in SRF cavities
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- ◆ Energetic Condensation
- ◆ Morphology of thin films produced by energetic condensation
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RRR of Nb thin films on sapphire and MgO substrates

- ◆ Nb thin films grown on sapphire and MgO crystals have demonstrated higher levels of RRR than were reported by the pioneers, and XRD spectra reveal crucial features



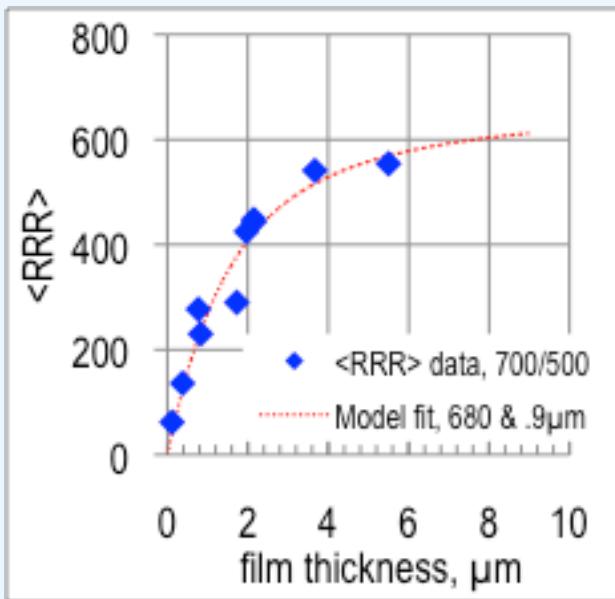
RRR-585 ($\pm 1\%$ error)
measured on 5 μ m film on
MgO

RRR-330 measured on a-
sapphire

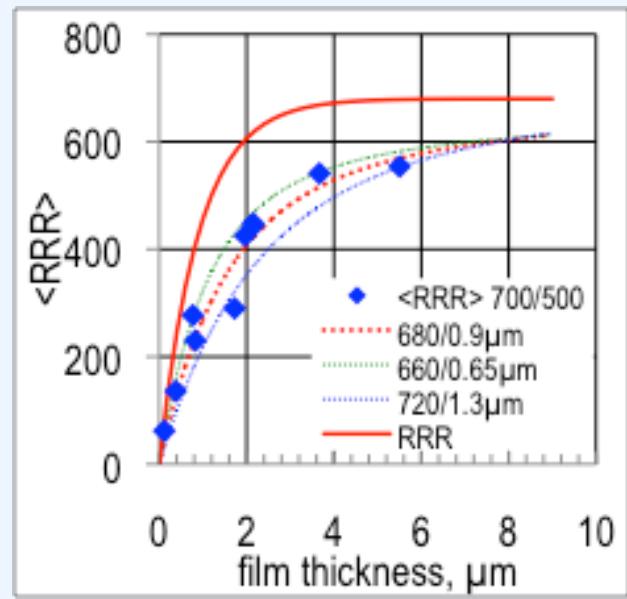
- ◆ M. Krishnan, E. Valderrama, B. Bures, K. Wilson-Elliott, X. Zhao, L. Phillips, Anne-Marie Valente-Feliciano, Joshua Spradlin, C. Reece, K. Seo, submitted to Superconducting Science and Technology

Nb on MgO: Local RRR vs. averaged $\langle RRR \rangle$

- ◆ $\langle RRR \rangle$ vs. film thickness



- ◆ Ad hoc model fit to $\langle RRR \rangle$ data



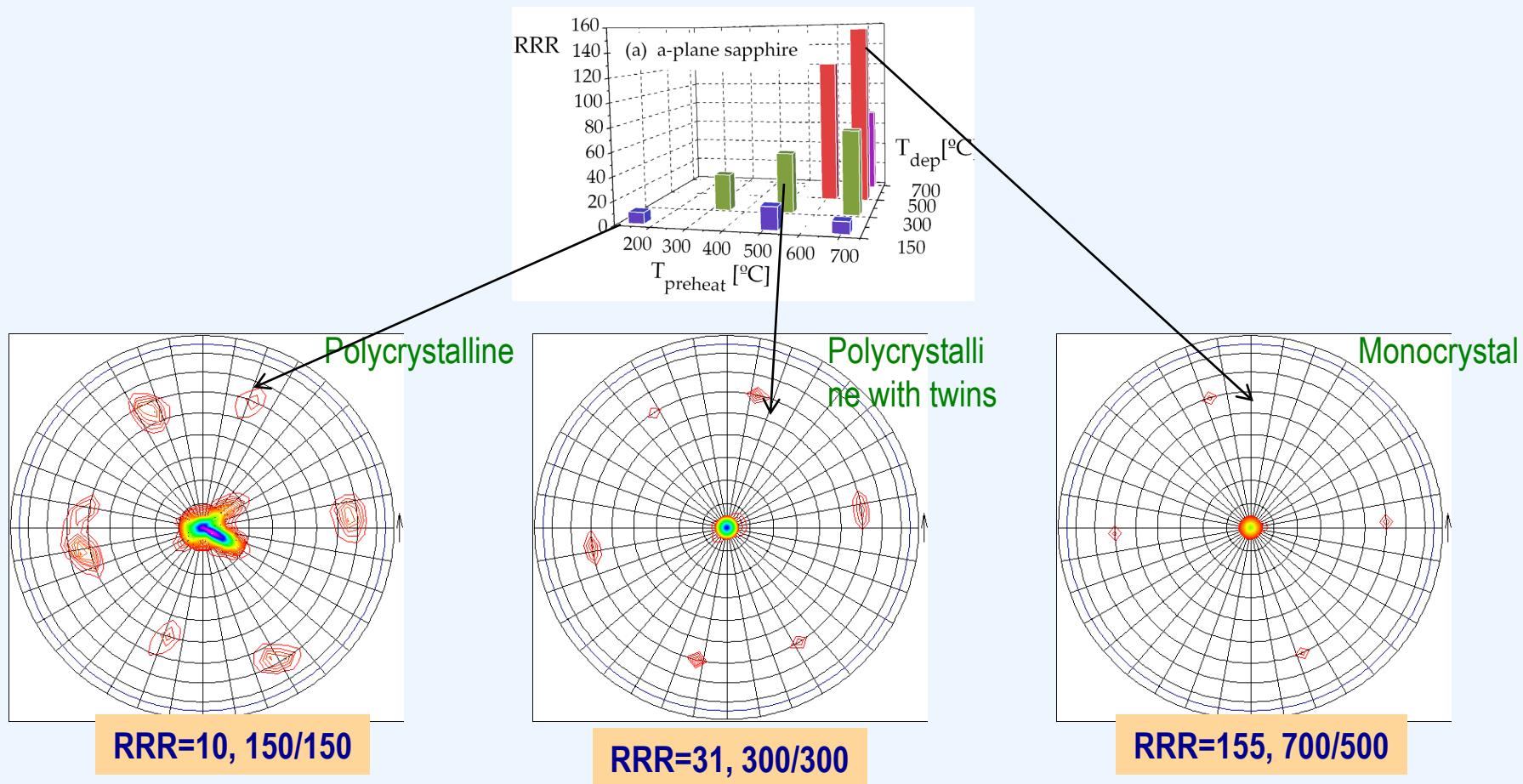
$$\langle RRR \rangle = \frac{1}{x_o} \int_0^{x_o} R_o * \left(1 - e^{-\frac{x}{x^*}} \right) dx = R_o \left[1 - \frac{x^*}{x} \left\{ 1 - e^{-\frac{x}{x^*}} \right\} \right]$$

$$RRR = R_o * \left[1 - e^{-\frac{x}{x^*}} \right]$$

G. Orlandi, C. Benvenuti, S. Calatroni, F. Scalabrin, *Expected dependence of Nb-coated RF cavity performance on the characteristics of niobium*, Proc. Of 6th workshop on RF Superconductivity, CEBAF, (1993)

RRR of Nb thin films on a-sapphire substrates

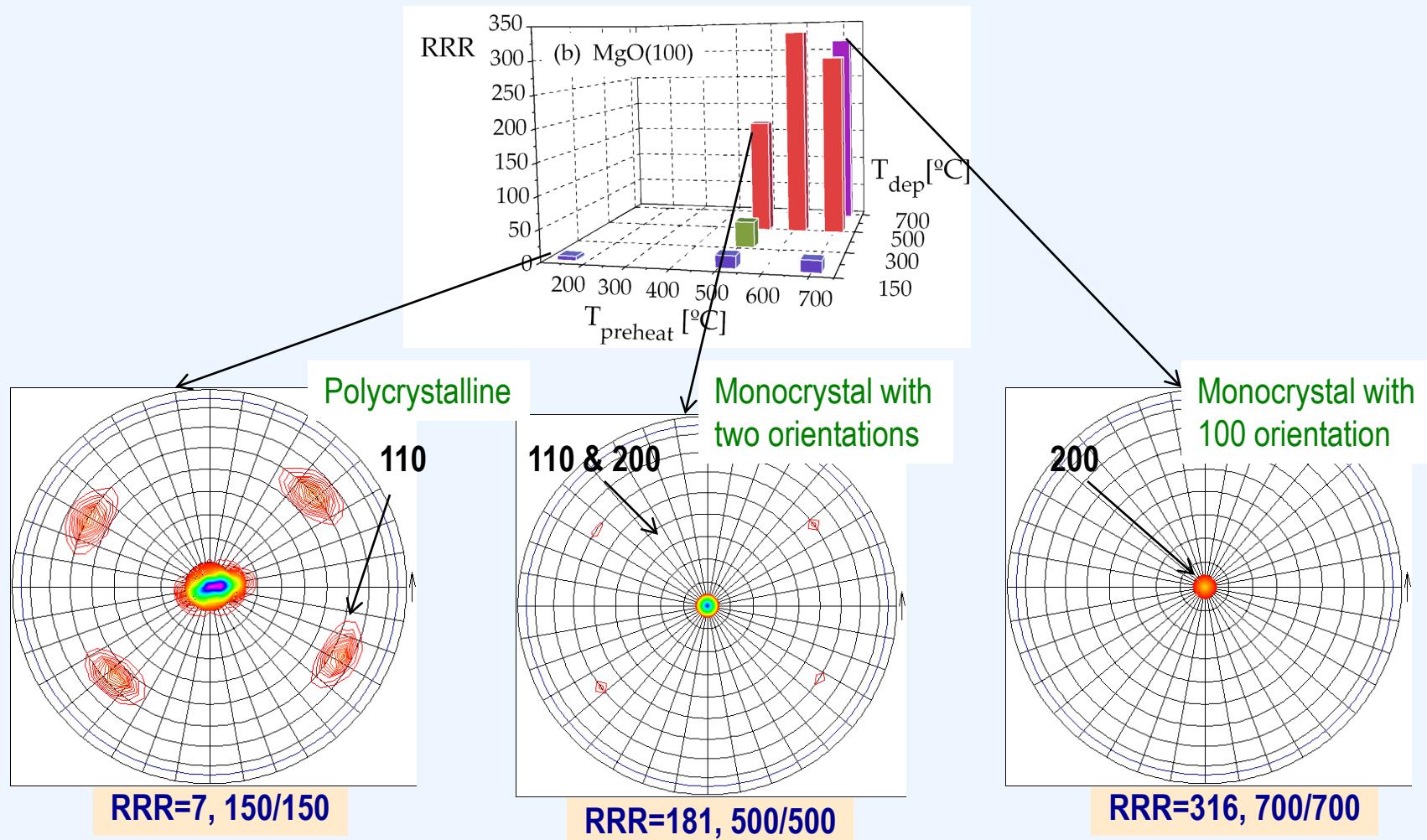
- ◆ XRD Pole Figures show that higher RRR correlates with higher crystalline order



- ◆ "Twin symmetry texture of energetically condensed niobium thin films on sapphire substrate (a-plane Al₂O₃)", X. Zhao, L. Philips, C. E. Reece, Kang Seo, M. Krishnan, E. Valderrama, Journal of Applied Physics, Vol 115, Issue 2, 2011, [in-press],

RRR of Nb thin films on MgO substrates

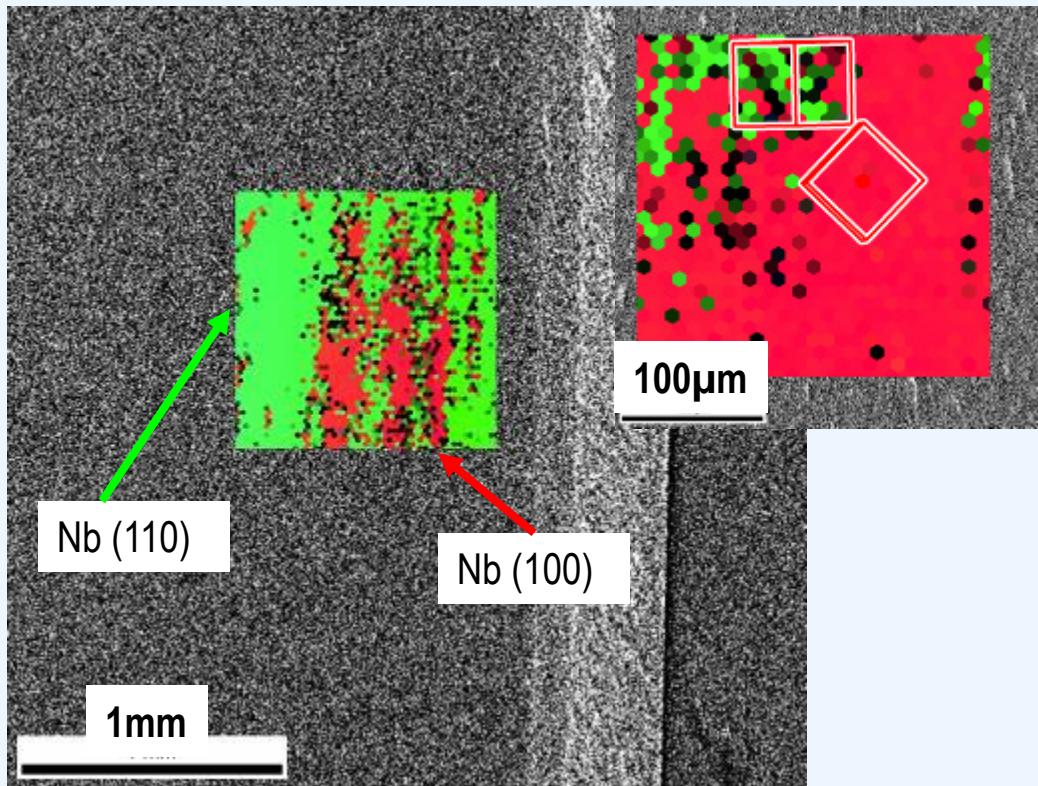
- ◆ Pole Figures show change in crystal orientation from 110 to 200 at higher temperature



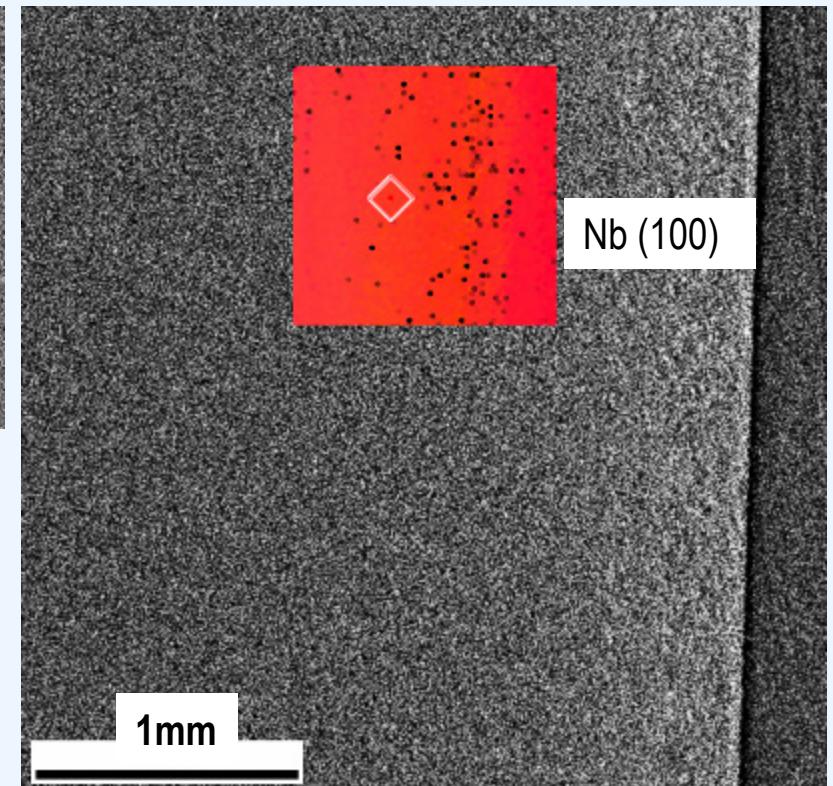
- ◆ Please visit poster THP0042 (given by Xin Zhao of JLab) for more details

- ◆ EBSD data shows intermixed Nb (110) and Nb (100) for lower RRR samples
- ◆ High RRR samples show pure Nb (100) for the entire surface

RRR = 196, 500/500



RRR = 333, 600/500



EBSD shows 110 to 100 transition (Pole figure captures the 200 plane):

Observations about bulk single crystal Nb orientation

PERFORMANCE OF SINGLE CRYSTAL NIOBIUM CAVITIES, P. Kneisel, G. Ciovati, TJNAF, Newport News, VA 23606, U.S.A.
W. Singer, X. Singer, D. Reschke, A. Brinkmann, Proceedings of EPAC08, Genoa, Italy MOPP136

PROGRESS ON LARGE GRAIN AND SINGLE GRAIN NIOBIUM – INGOTS AND SHEET AND REVIEW OF PROGRESS ON LARGE GRAIN AND SINGLE GRAIN NIOBIUM CAVITIES, P. Kneisel, Proceedings of SRF2007, Peking Univ., Beijing, China

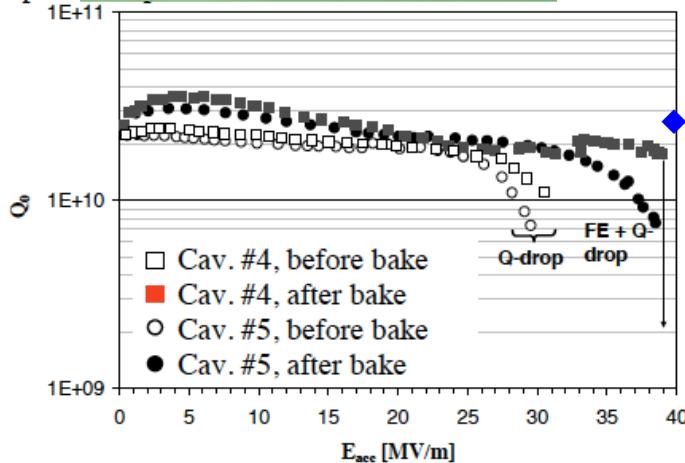
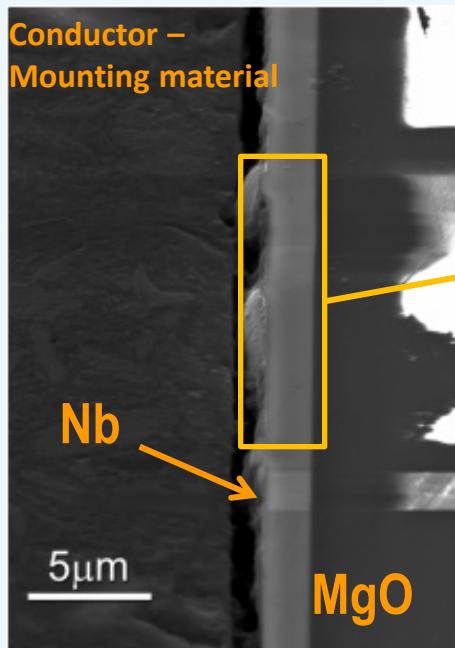


Figure 4: Q_0 vs. E_{acc} at 2 K for single crystal cavities #4 and #5 (best performance).

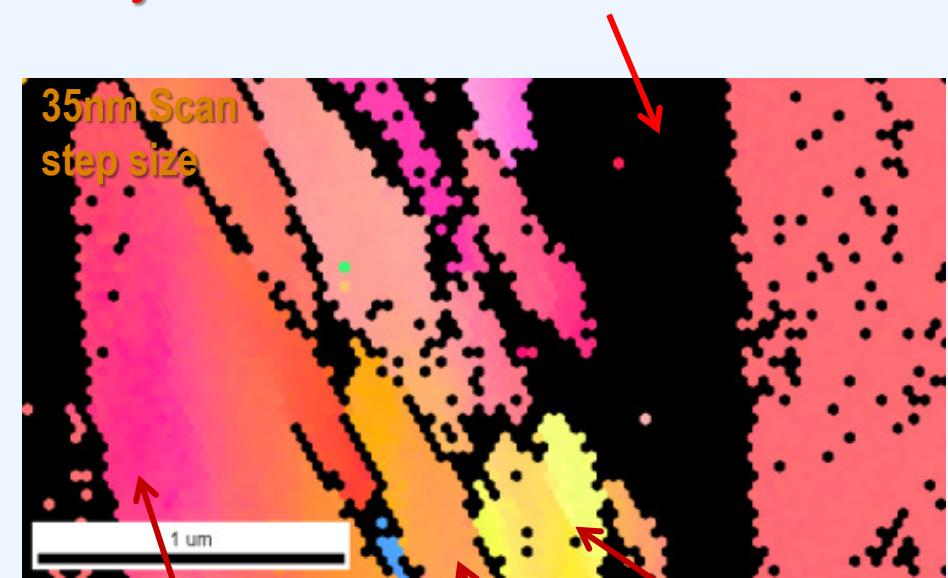
- ◆ Cavity #5 showed a different behavior than all other single crystal/large grain cavities after baking: the Q-drop did not disappear after 12 hours. The crystal orientation of the single crystals of this cavity was (110) with a tilt against the surface. For cavity #4 the crystal orientation was (100).
- ◆ The surface of both cavities appeared quite different after BCP: whereas cavity #4 exhibited a very smooth, shiny surface, the surface of cavity #5 was “rough” (orange peel/fish scale appearance) and less shiny.
- ◆ Obviously, there is a difference in the reaction of the BCP chemicals at different crystal orientations {D. Baars et al., “Crystal orientation effects during fabrication of single or multi-crystal Nb SRF cavities”, SRF07, Beijing, Oct. 2007, TH102; <http://www.pku.edu.cn/academic/srf2007/proceeding>}

Could CED (Energetic Condensation) be used to grow (100) Nb films on existing Nb cavities to help improve performance?

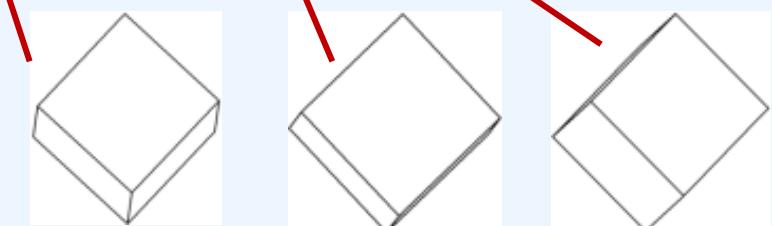
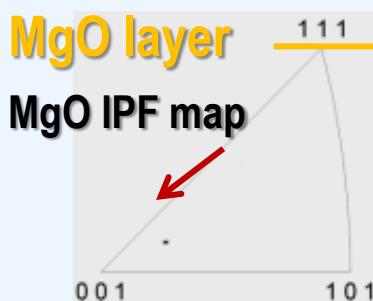
BSE image – Cross sectional view

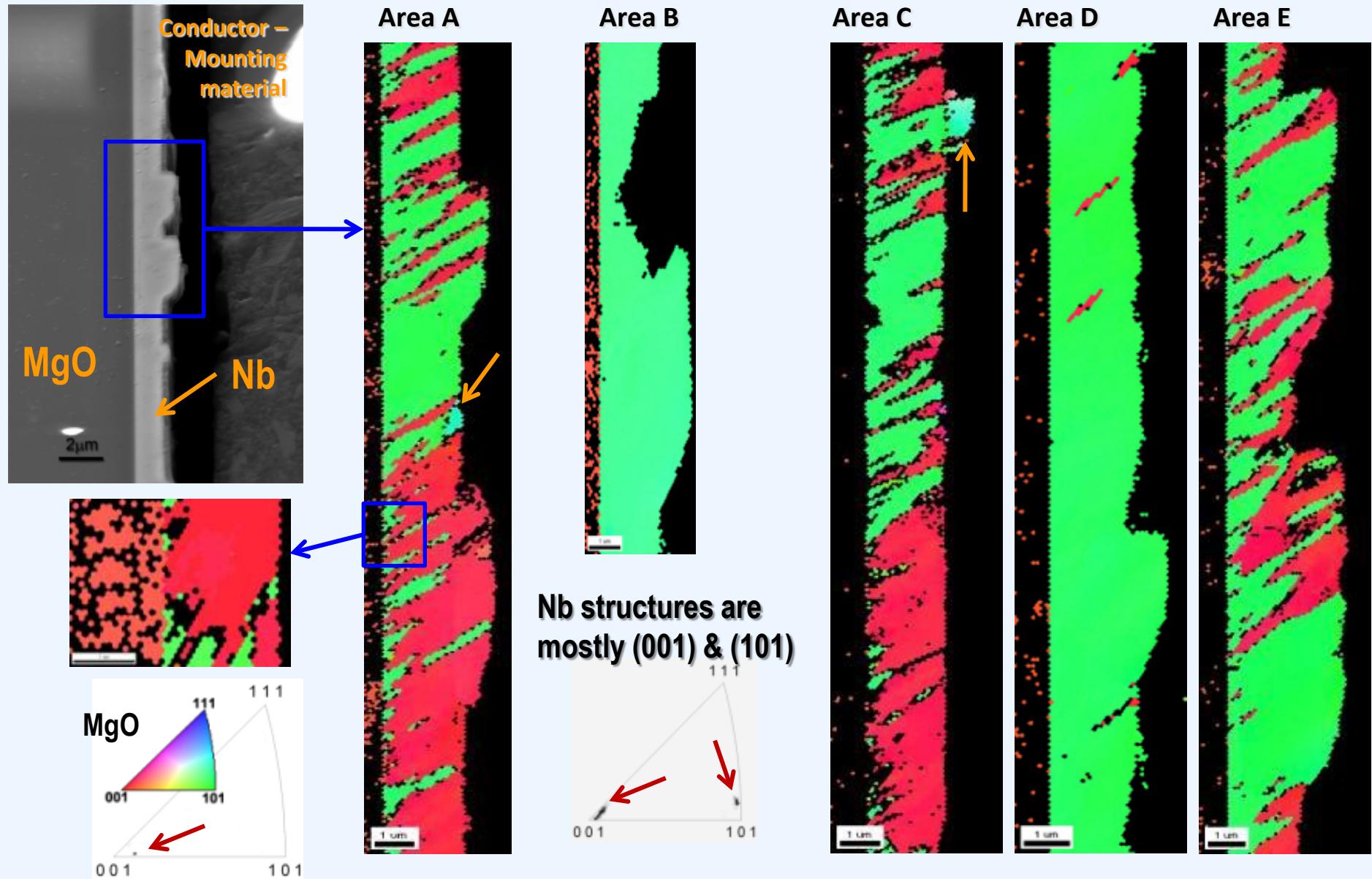


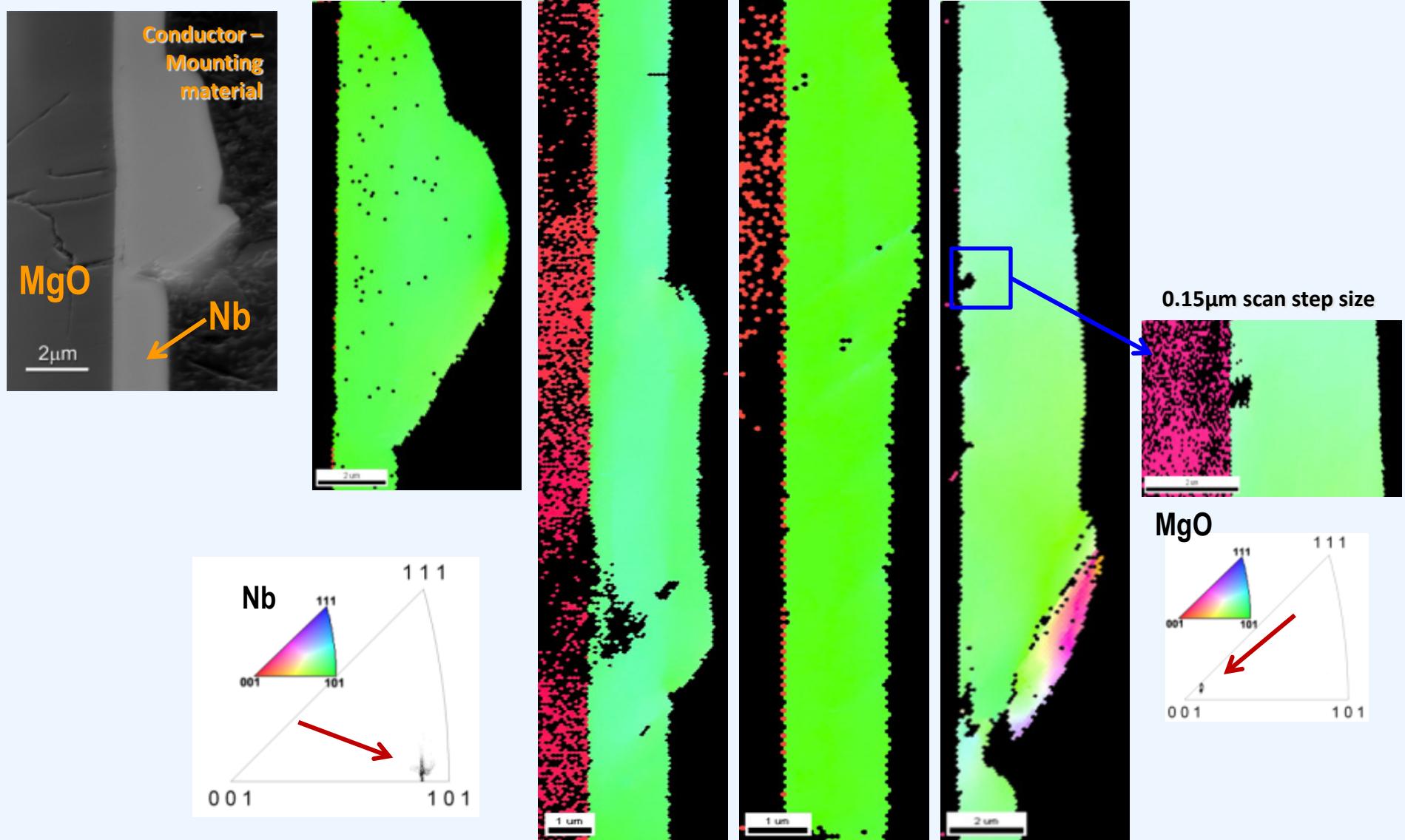
Lower CI values between Nb matrix and MgO substrate indicate that there could be an amorphous or non-structured layer between them

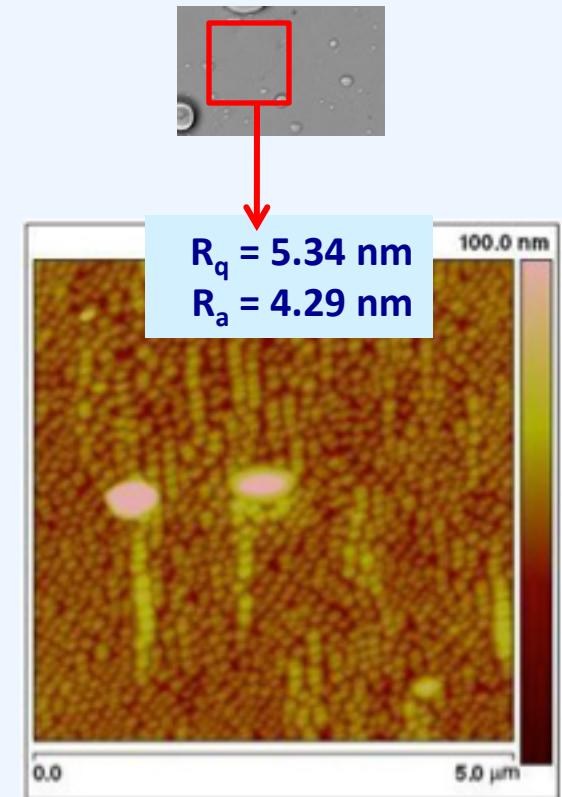
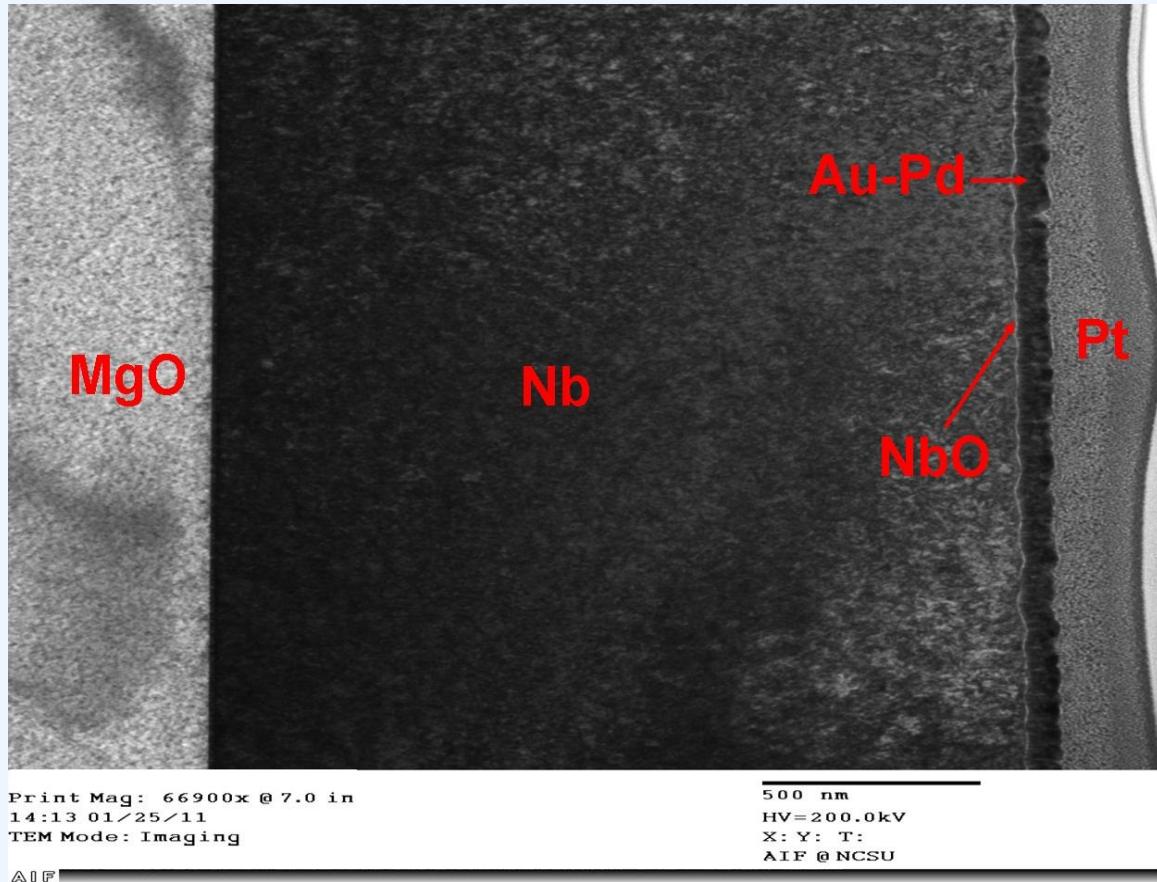


Nb thin film layer



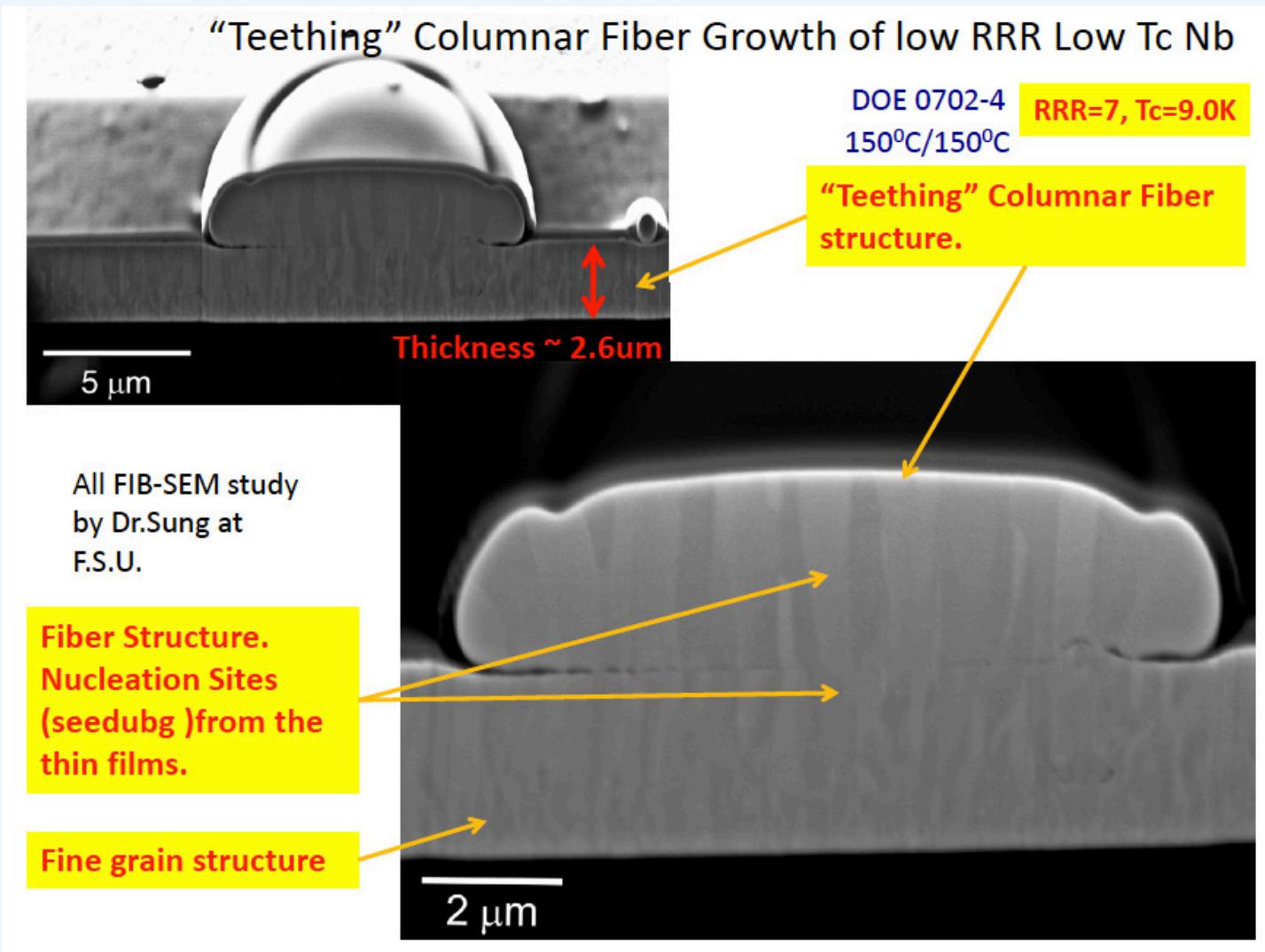






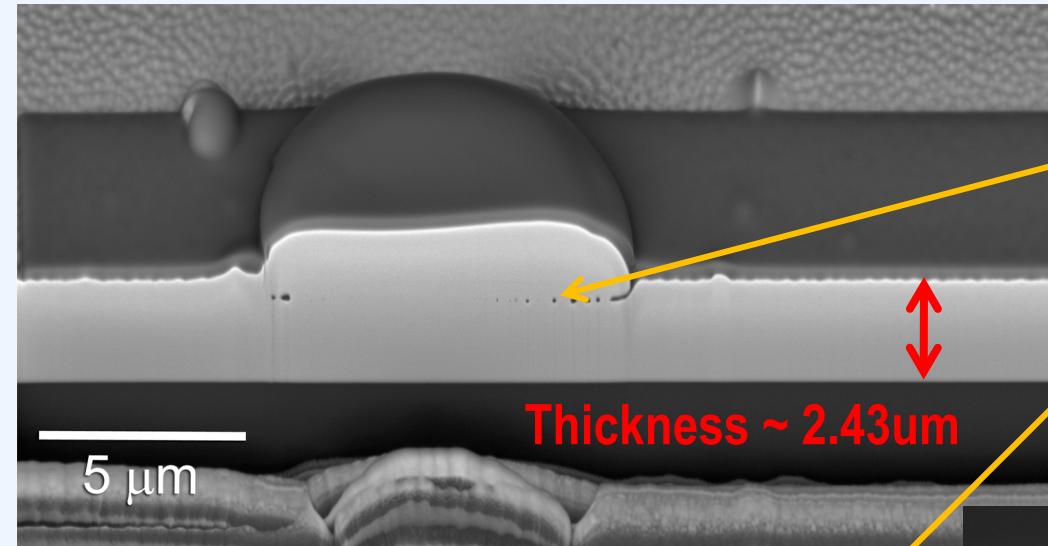
- ◆ Energetic Condensation (subplantation) physics drives an adhesive, non-porous, dense interface between substrate and Nb film
- ◆ Nb surface is smooth ($\sim 5\text{nm}$ roughness)

“Mold” effect of subplanted Nb films: low RRR film



The macroparticle acquires the same crystallite structure as does the underlying Nb thin film that preceded it . This is for a low RRR film.

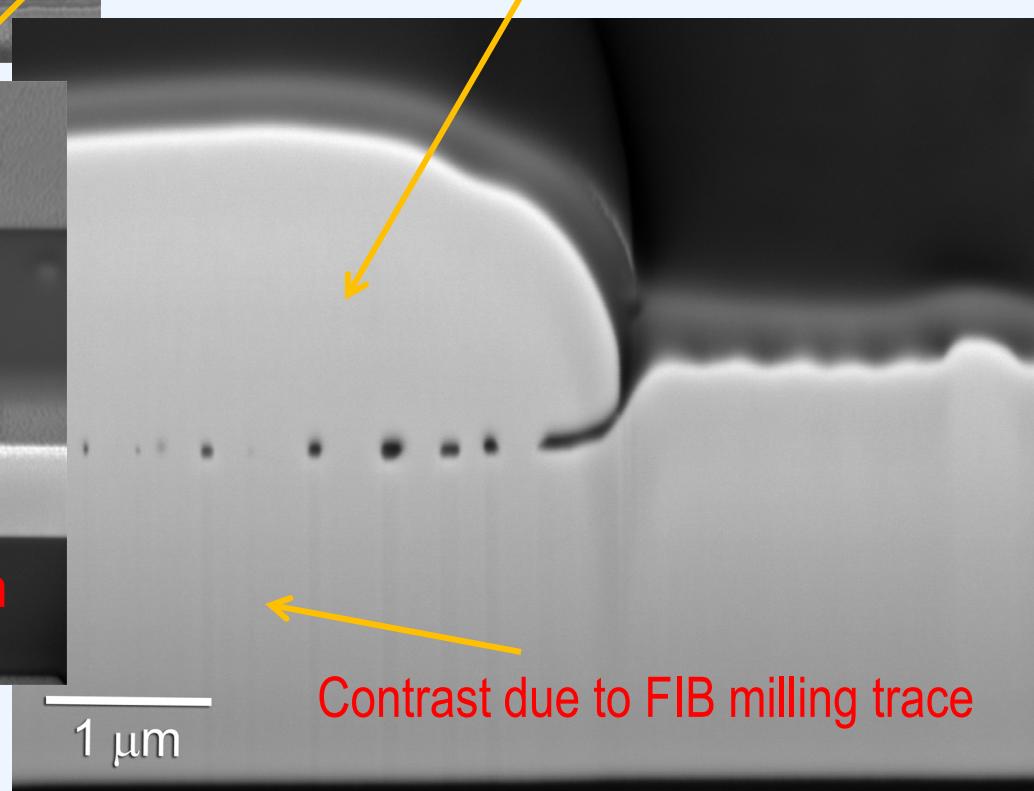
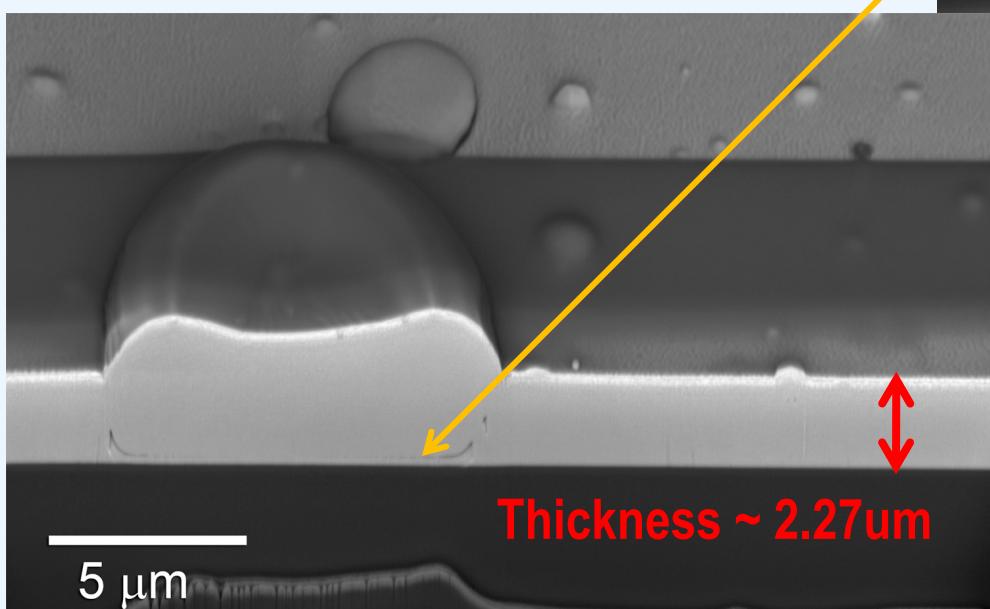
“Mold” effect of subplanted Nb films: high RRR film



This macro landed on 2.4 μm Nb film

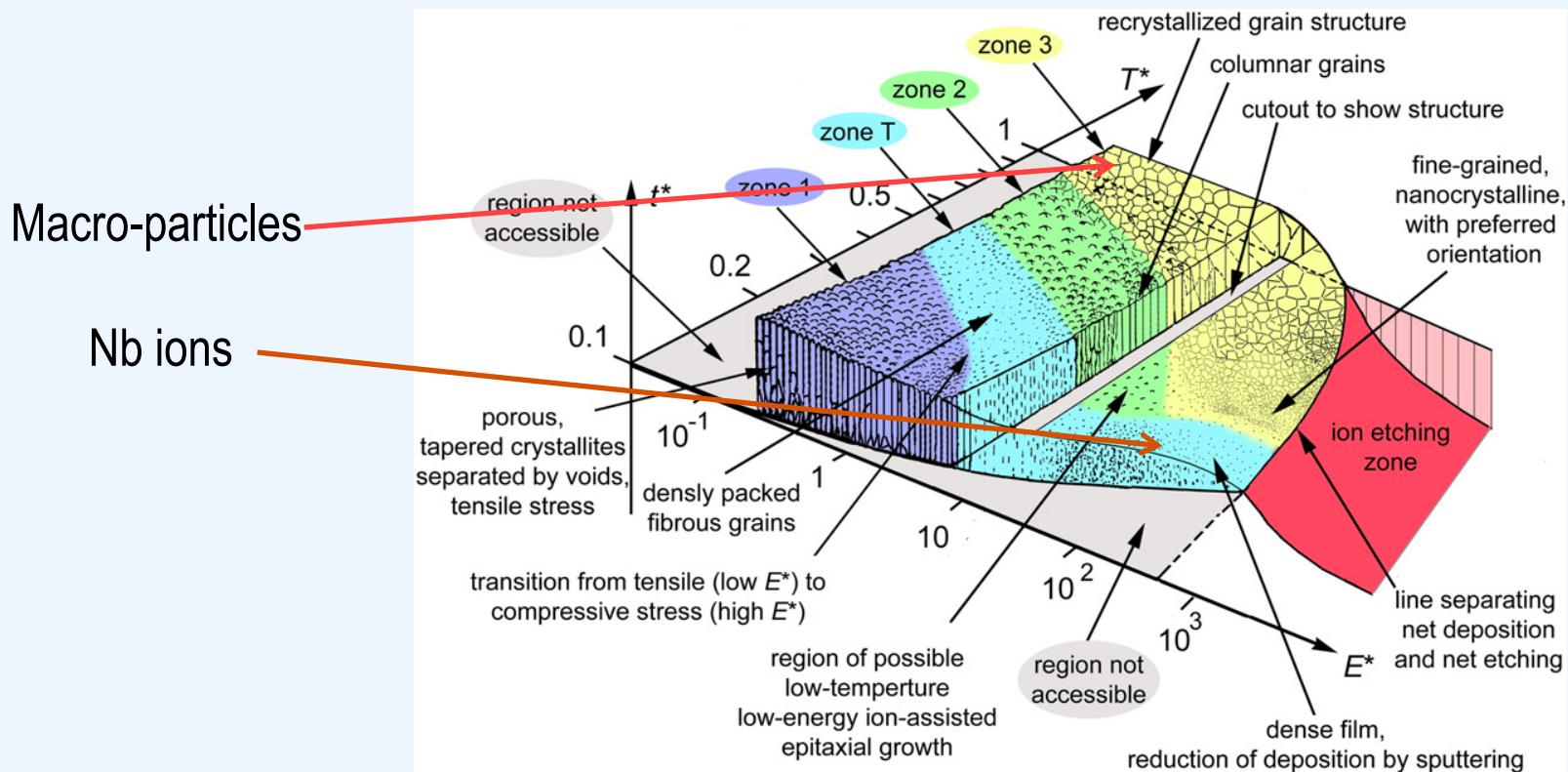
This macro landed near MgO surface

No Columnar structure; XRD shows (100) single crystal



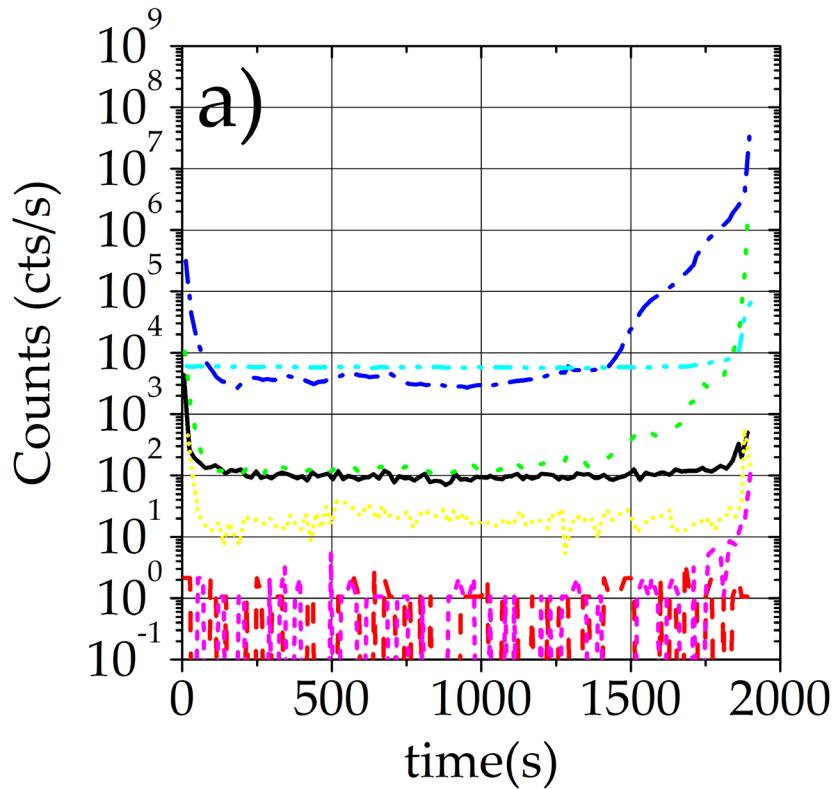
Revisit Andre Anders' SZD

- ◆ Macro-particles appear to have the same crystal structure as subplantation grown films
- ◆ Macroparticles arrive at surface with very low kinetic energy but $T/T_m \sim 1$

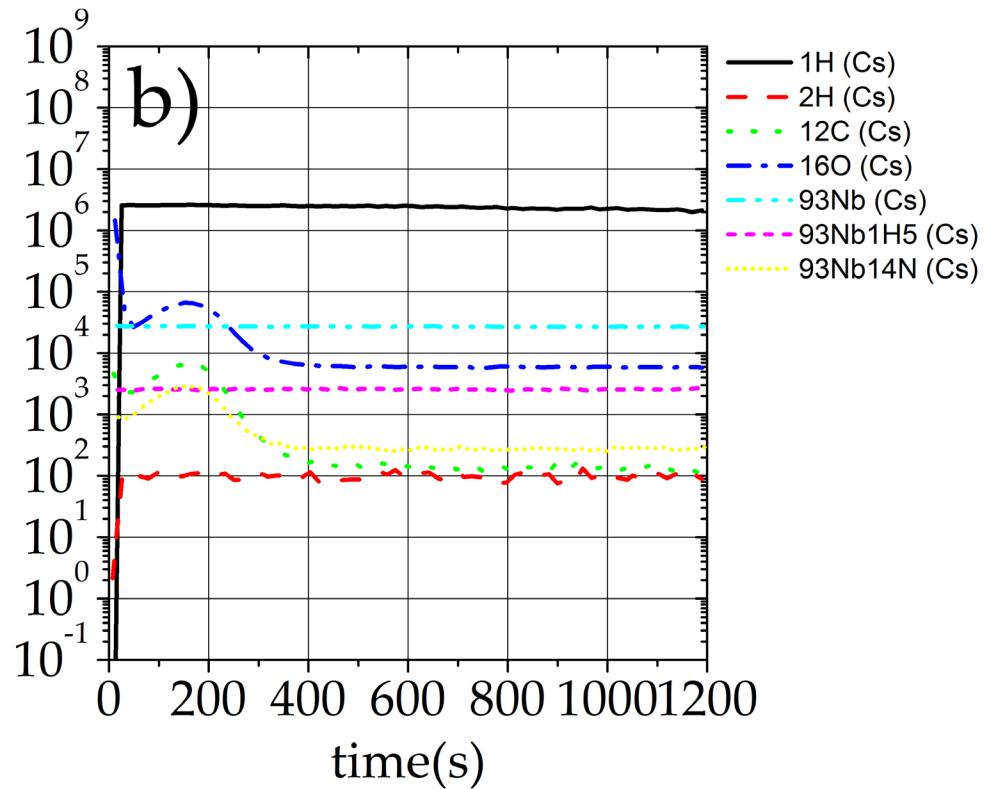


Can we develop a “hybrid” growth concept in which Energetic Condensation plants the seed and then pure molten metal is poured on this seed, to develop a highly crystalline order via the “mold” effect?

SIMS with Cs beam of high RRR Nb films:



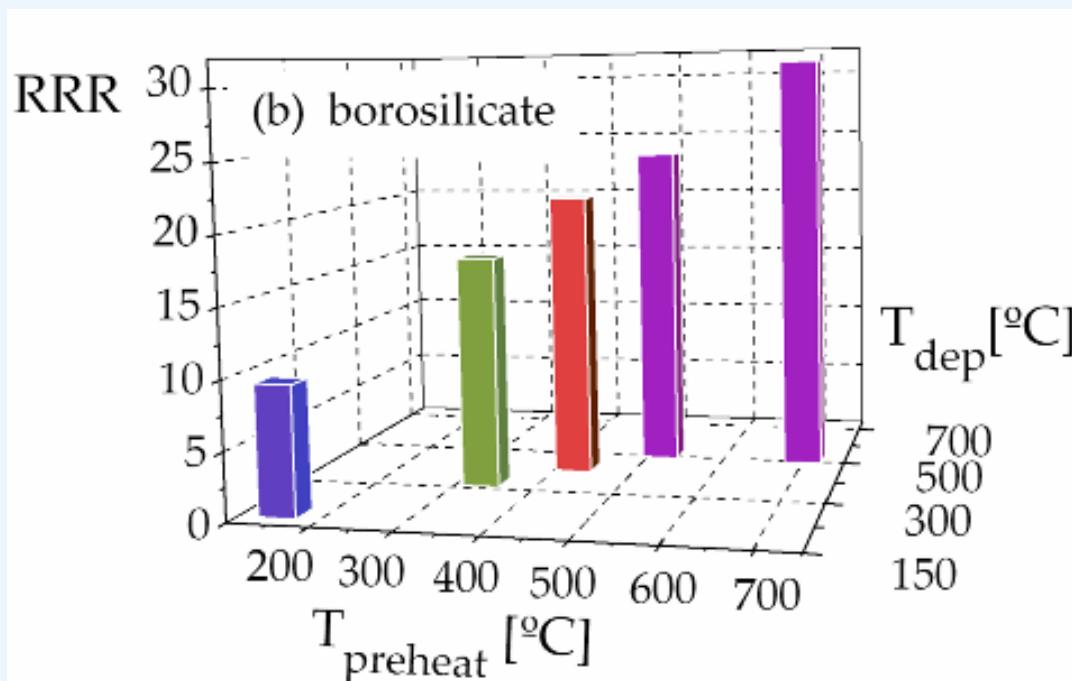
Nb (100) on MgO: RRR=442



Bulk Nb sample: RRR~300

H count rate (normalized) in thin films is 7×10^3 times lower than in bulk Nb!

- ◆ Nb thin films grown on amorphous borosilicate show a similar trend of higher RRR with higher substrate temperature



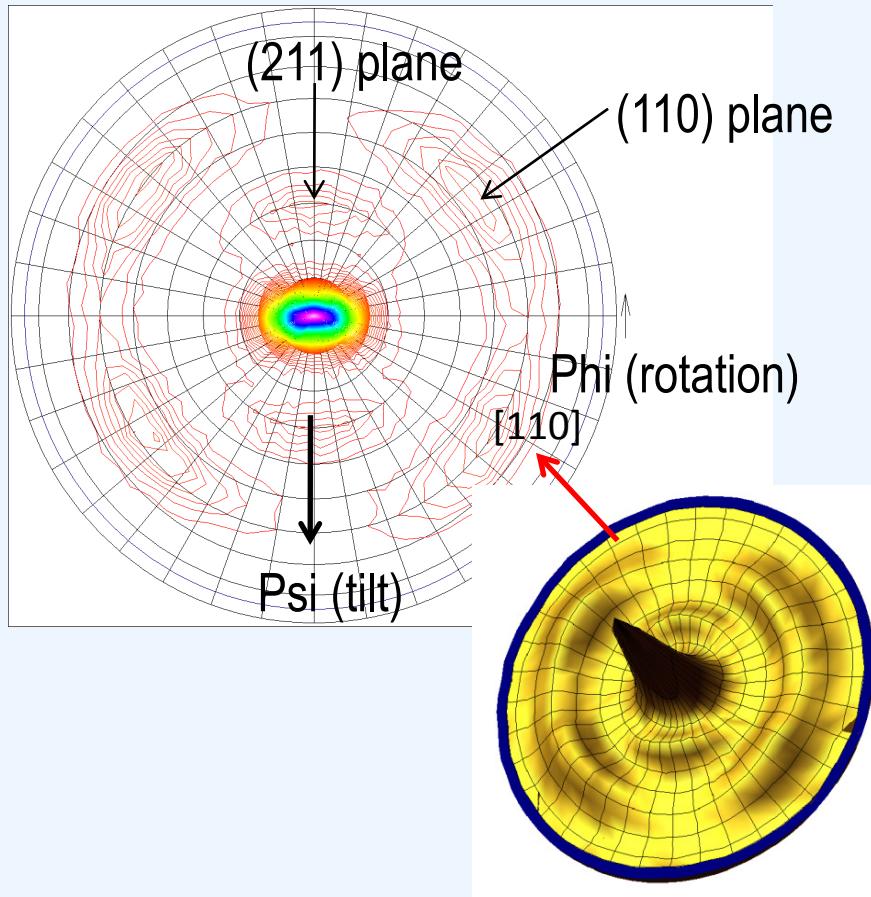
One option for Nb-on-Cu growth is to first “amorphize” the substrate by high energy “subplantation”, then attempt to drive Nb crystal growth
Aluminum substrates would also use this approach. *Borosilicate is a proxy*

Please visit THPO069 on Thursday: Nb Film Growth on Crystalline and Amorphous Substrates” Dr. Enrique Valderrama

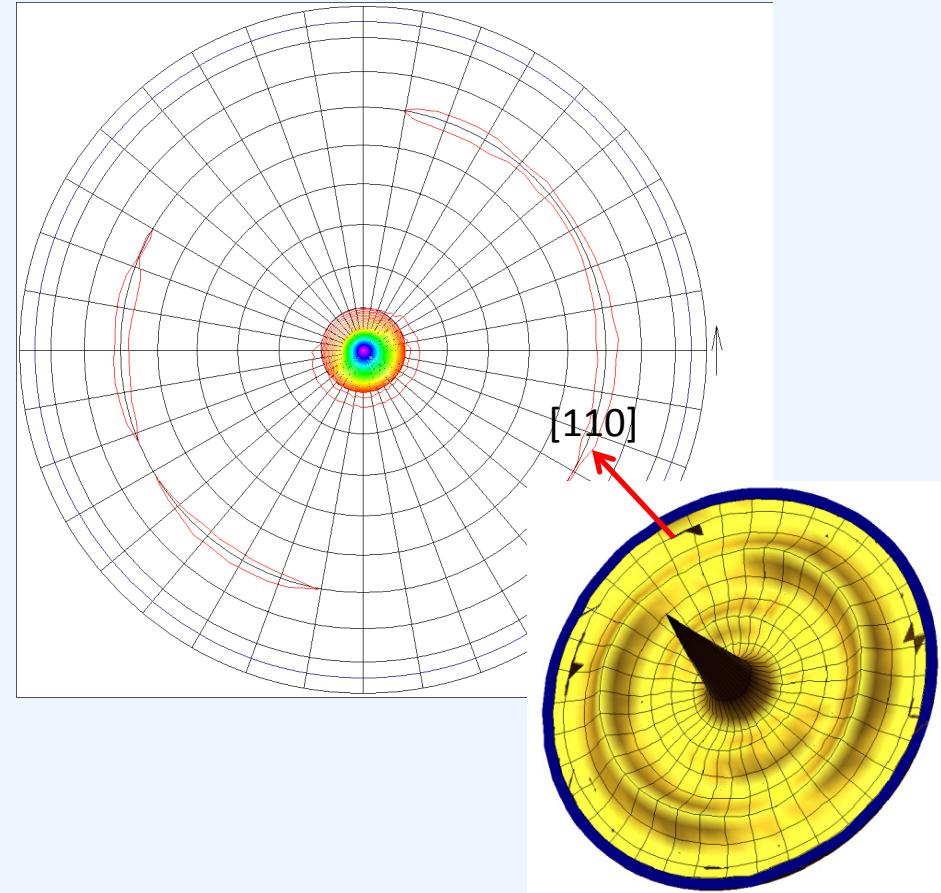
XRD Pole Figures for Nb thin films grown on Borosilicate

Subplantation physics of energetic condensation at work here

(110) Nb on Borosilicate at 150/150C



(110) Nb on Borosilicate at 400/400C



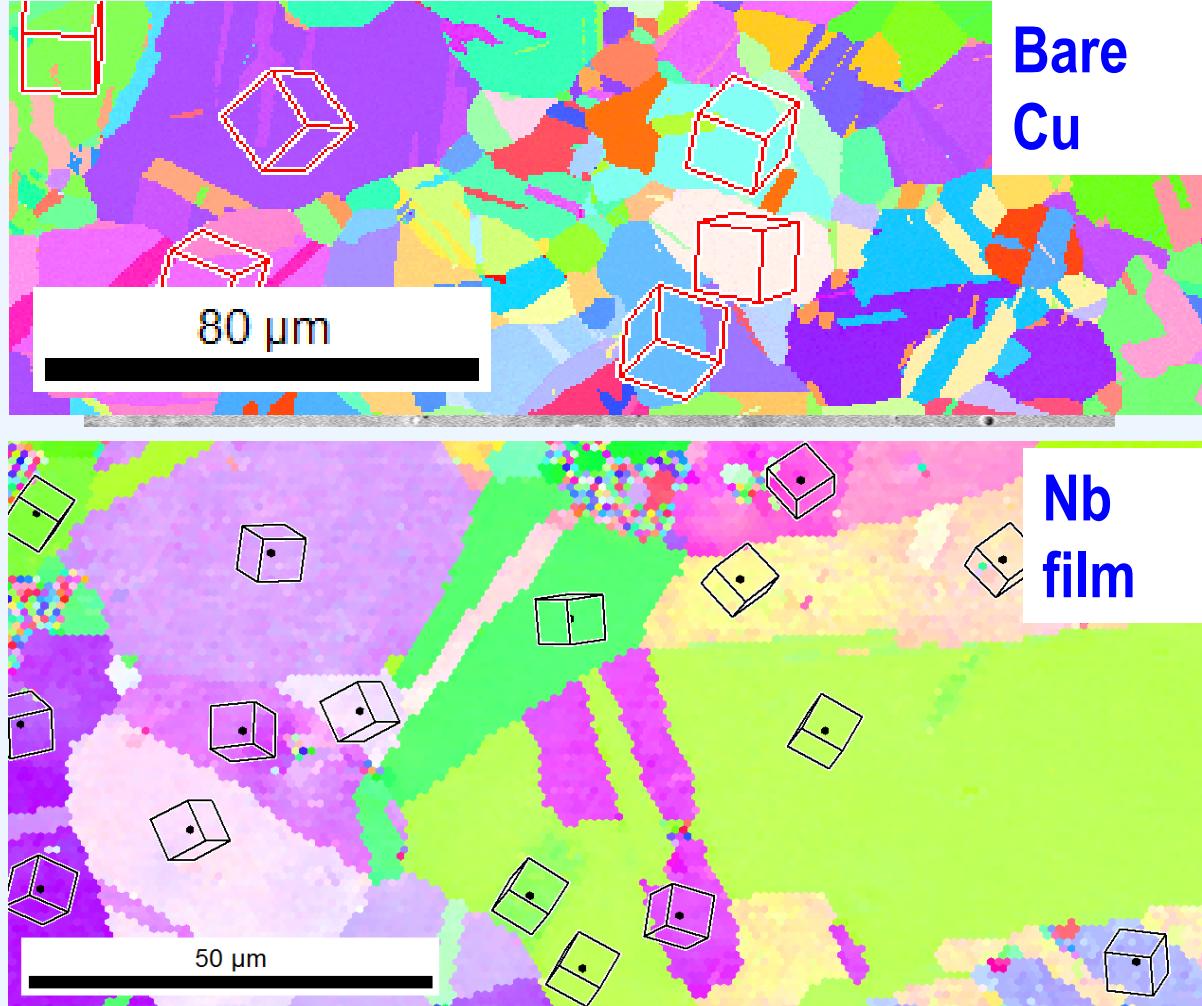
A strong [110] Nb fiber structure perpendicular to the substrate

At higher coating temperature, in-plane texture shows that [110] fiber texture is highly oriented to the substrate



~50 μ m grains of Nb measured in 0.4 μ m thick films on Cu

"Large crystal grain niobium thin films deposited by energetic condensation in vacuum arc", X. Zhao, A.-M. Valente-Feliciano, C. Xu, R. L. P. Geng, L., C. E. Reece, K. Seo, R. Crooks, M. Krishnan, A. Gerhan, B. Bures, K. W. Elliott, and J. Wright, Journal of Vacuum Science & Technology A 27, 620-625 (2009).



Working Distance: 15.000000

Number of points: 13094

Number of good points:
13093

150.00 microns x 74.48
microns

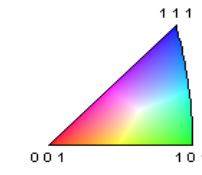
Step: 1.00 microns

Average Confidence Index:
0.42

Average Image Quality:
2633.56

Average Fit [degrees]: 1.35
EBSD Image of Sample TF-AASC-CED-
Nb-Cu-103,CED™, Cu substrate T=400C

Color Coded Map Type: Inverse Pole Figure [001]
Niobium



Boundaries: <none>

Energetic Condensation demonstrated growth of very large Nb grains on Cu.
Please see Anne-Marie's talk later for recent RRR and other data from an ECR source

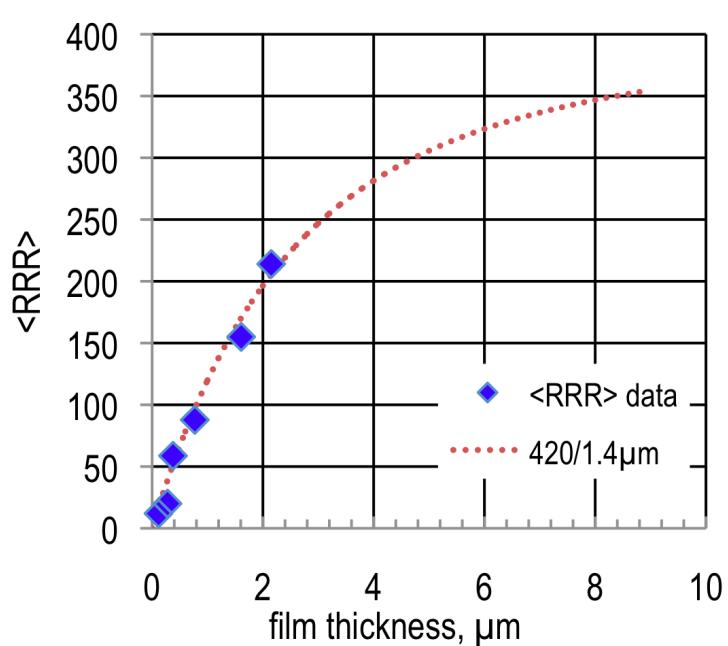


Vielen Dank

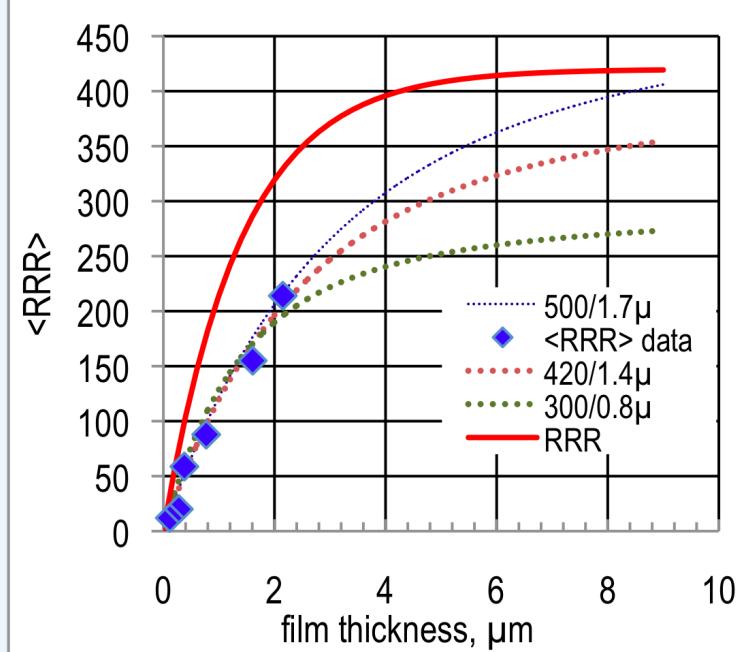
Fragen, bitte?

Nb on *a*-sapphire: Local RRR vs. averaged <RRR>

◆ <RRR> vs. film thickness



◆ Ad hoc model fit to <RRR> data

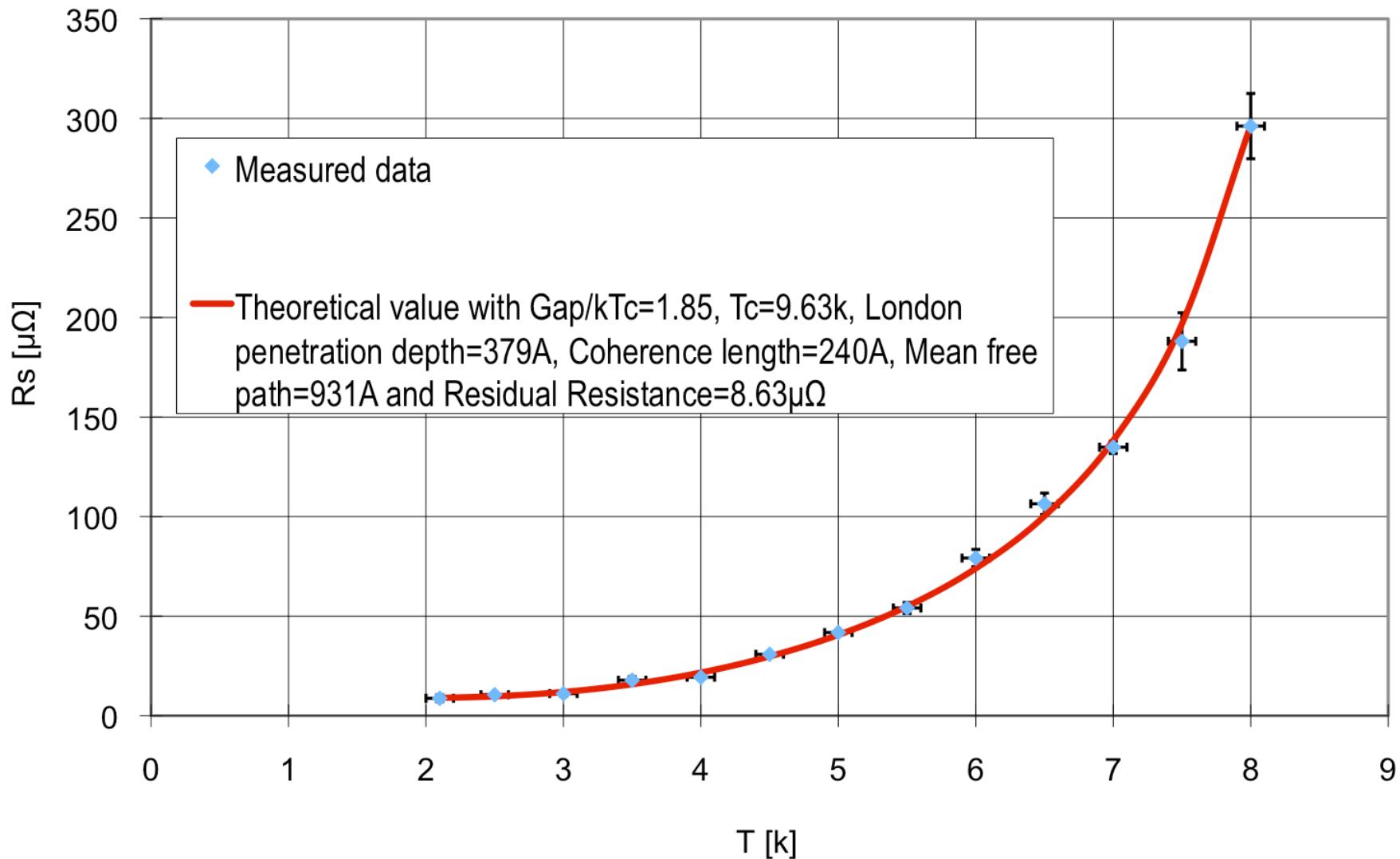


$$\langle RRR \rangle = \frac{1}{x_o} \int_0^{x_o} R_o * \left(1 - e^{-\frac{x}{x^*}} \right) dx = R_o \left[1 - \frac{x^*}{x} \left\{ 1 - e^{-\frac{x}{x^*}} \right\} \right]$$

$$RRR = R_o * \left[1 - e^{-\frac{x}{x^*}} \right]$$

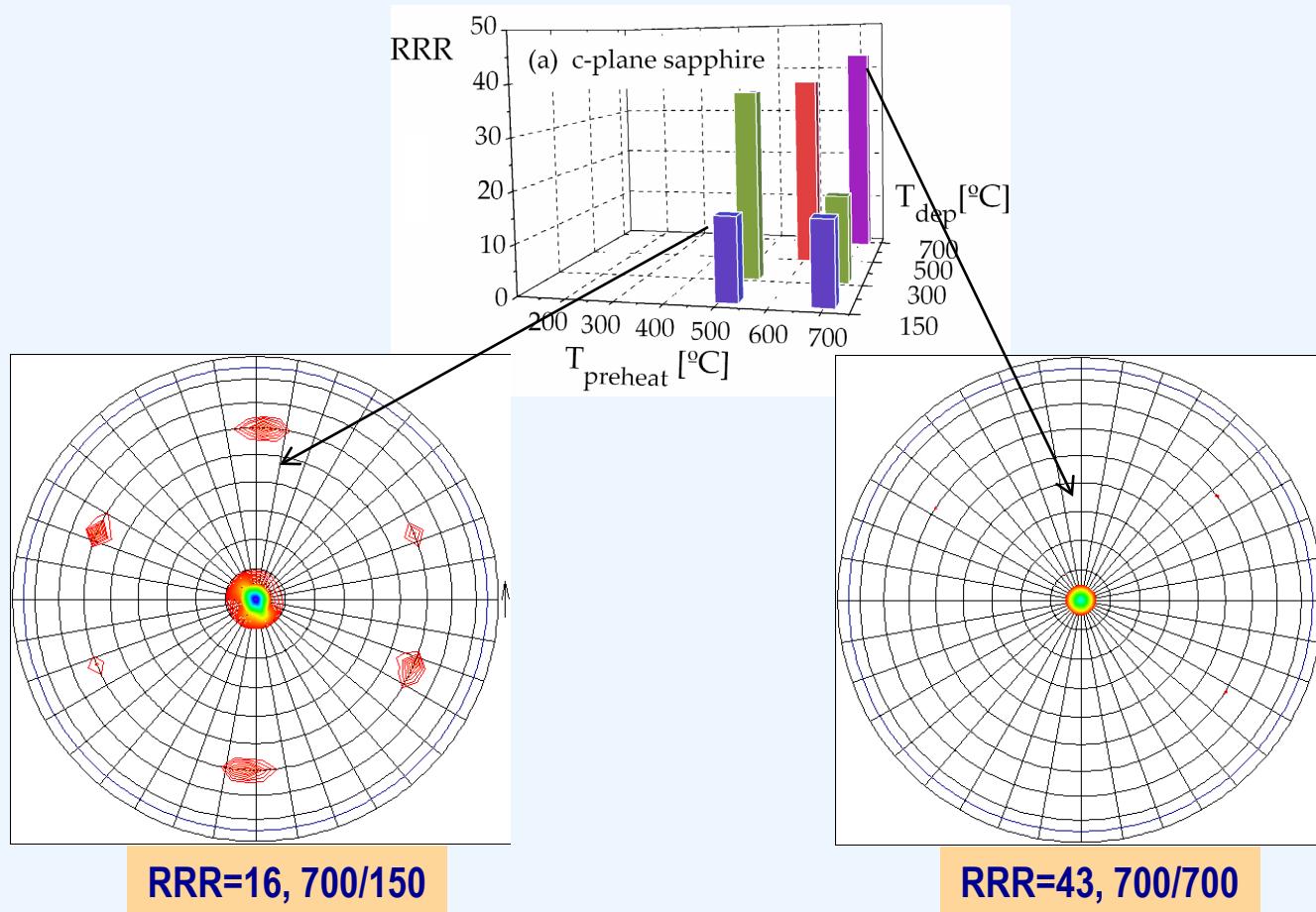
Thicker films must be analyzed before we can do a better model fit

R_s vs. T: thin film Nb on Cu sample TF-AASC-CED-103; EP, annealed at 750 C, then EP again



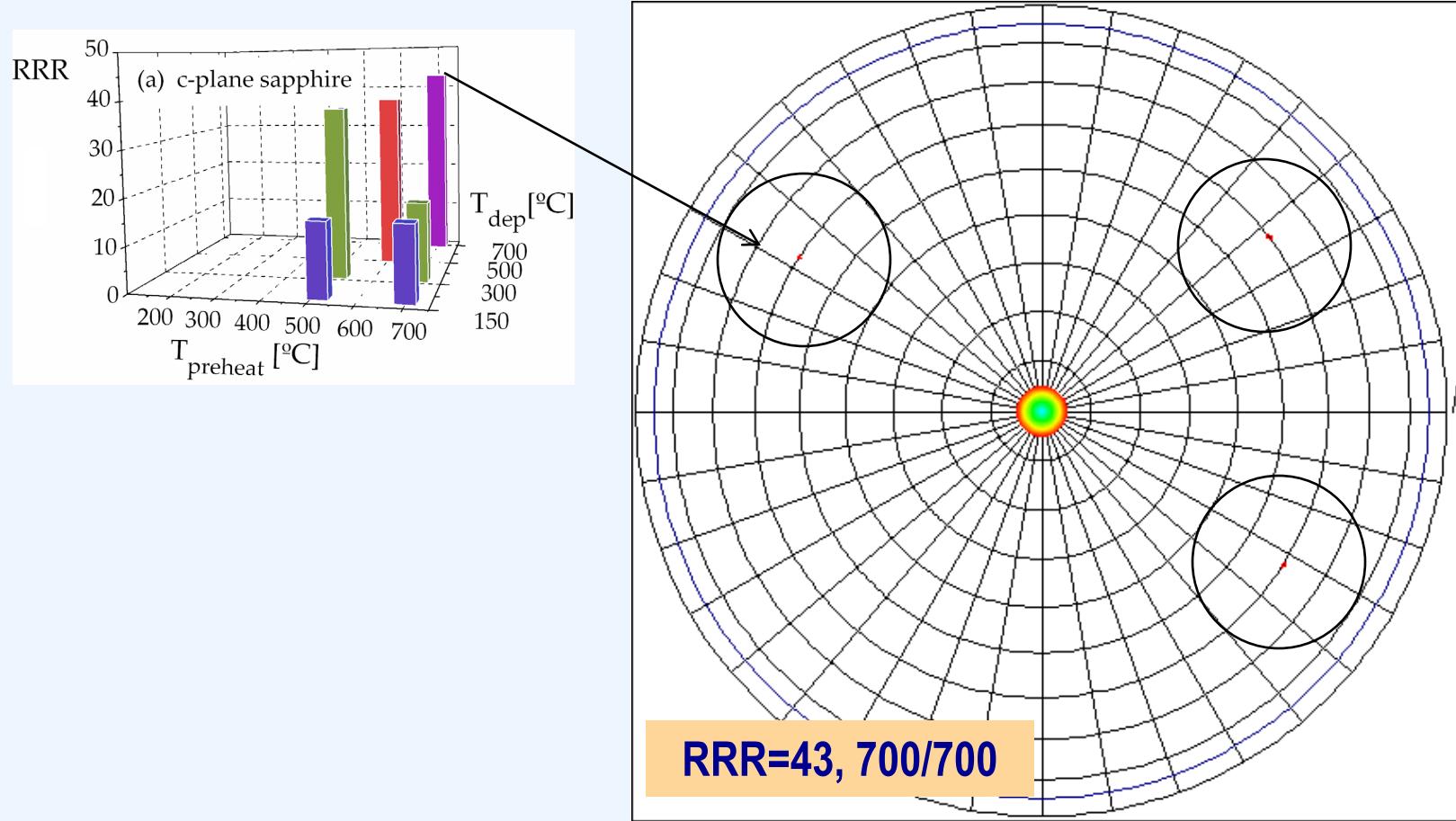
RRR of Nb thin films on c-sapphire substrates

- ◆ Pole Figures show better crystal structure at higher temperature



RRR of Nb thin films on c-sapphire substrates

- ◆ Pole Figures show better crystal structure at higher temperature



- ◆ Despite high crystalline order, RRR is only 43. High order is a necessary condition for high RRR, but film might have impurities that limit electron mean free path.

sample ID	RRR	error bar	T_c	# of shots	delta, μm	anneal temp	dep temp	substrate	base pressure
CED-113010-66	541	10%	9.30	20000	3.67	700	500	MgO(100), MTI, 2 x1 cm^2	2.60E-08
CED-120310-68	554	25%	9.30	30000	5.50	700	500	MgO(100), MTI, 1 x1 cm^2	2.70E-08
CED-120310-69	585	1%	9.34	30000	5.5	700	500	MgO(100), MTI, 1 x1 cm^2	2.70E-08